

Epitaxy in the development of LEDs

Jean-Yves Duboz

CRHEA-CNRS

Valbonne Sophia Antipolis

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Nice Airport



Antibes



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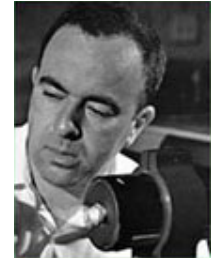
Epitaxy (GaN, ZnO, SiC, graphene)

Characterization (structural, optical)

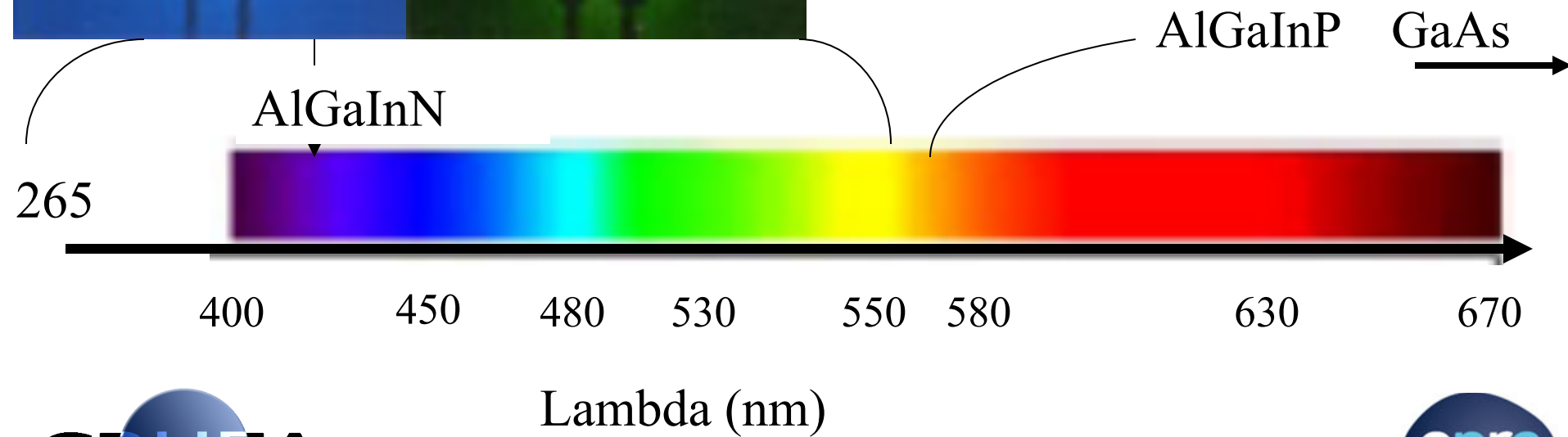
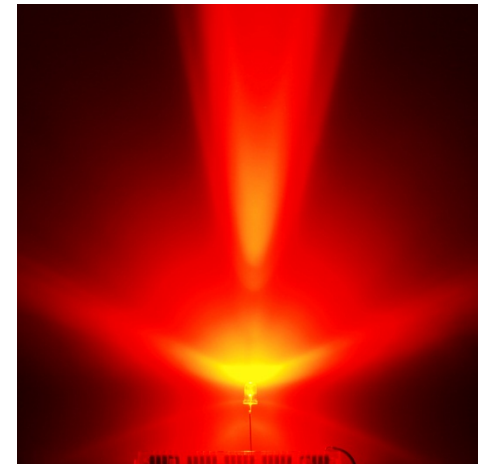
Device fabrication (LED, laser, transistors....)

History of LEDs

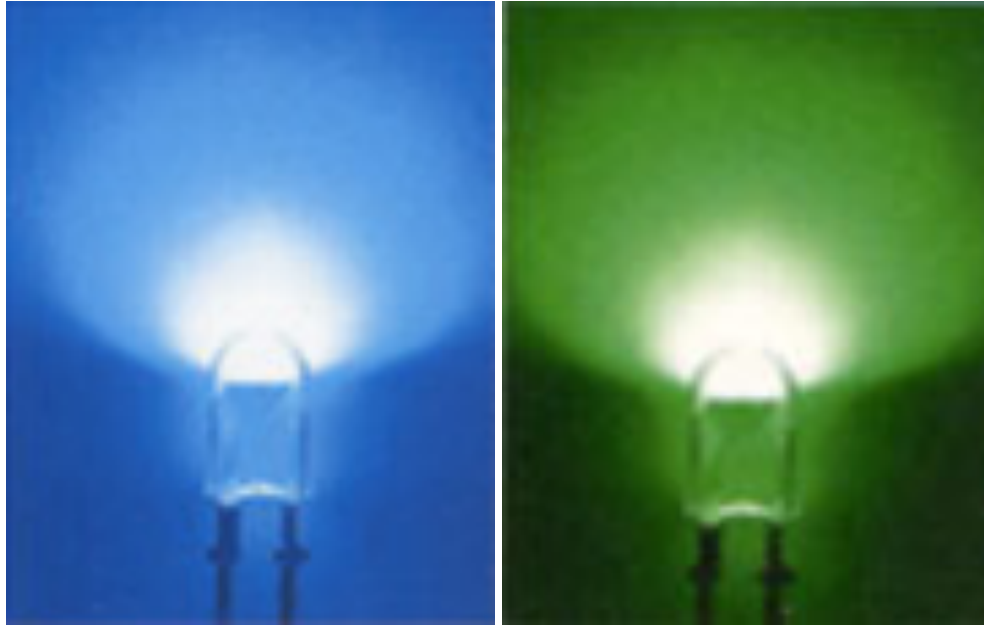
- LED first discovery : the first known observation of electroluminescence was made in 1907 by H. J. Round using SiC Schottky diode.
- In 1955, Rubin Braunstein of the Radio Corporation of America reported on infrared emission from gallium arsenide (GaAs) and other semiconductor alloys, patented in 1961
- In 1962, Nick Holonyak Jr., of the General Electric Company developed the first practical visible-spectrum LED. He is seen as the "father of the light-emitting diode".
- In 1972 first yellow LED and 10x brighter red and red-orange LEDs (by George Craford)
- 1993 Shuji Nakamura of Nichia Corporation of Japan demonstrated the first high-brightness blue LED based on InGaN. Beginning of the quest for white LEDs for solid state lightning. Nobel prize 2014.



LED



LED



Initial business

LED for signaling (traffic light), displays...

Monochromatic emission: low tolerance

$\Delta\lambda < \text{few nm}$

Low- medium power 10-50 mW



Current business

LED for lighting

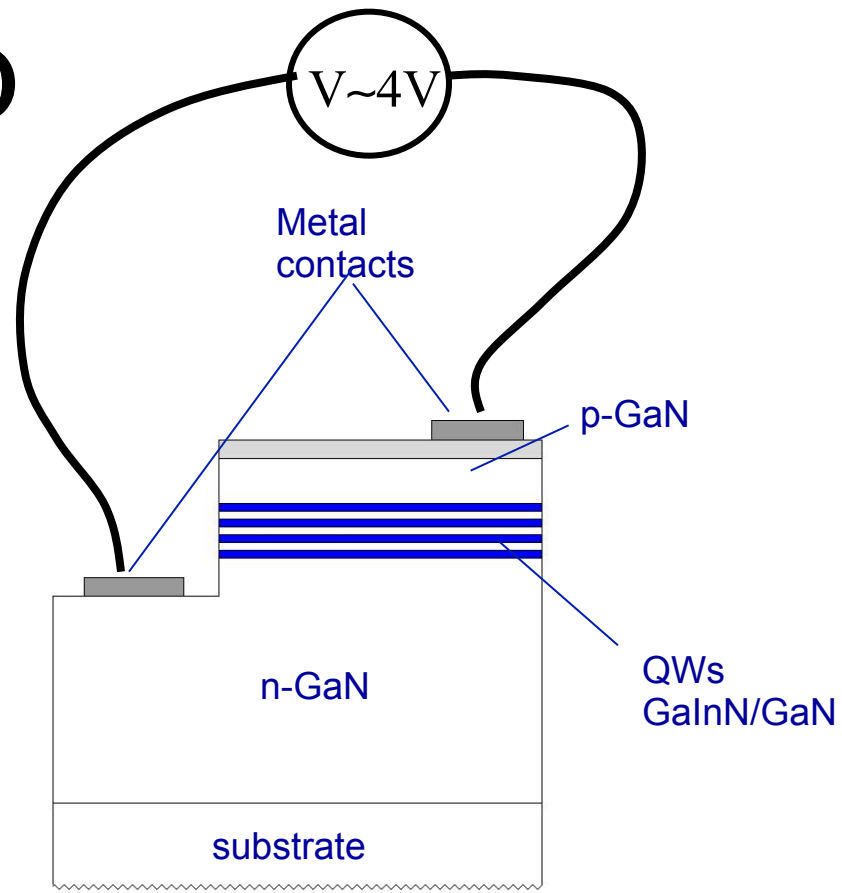
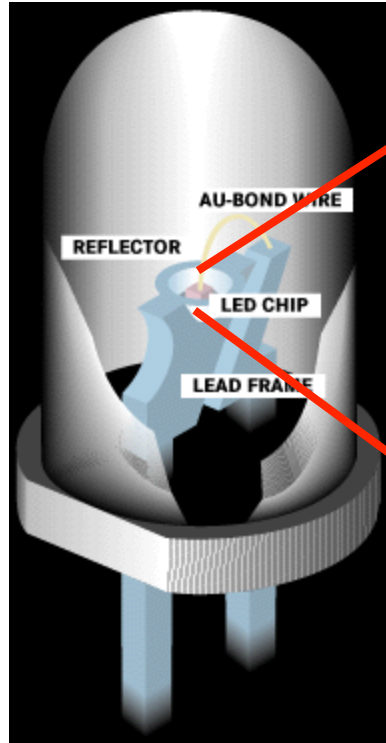
Color rendering index, white temp.

High power: W

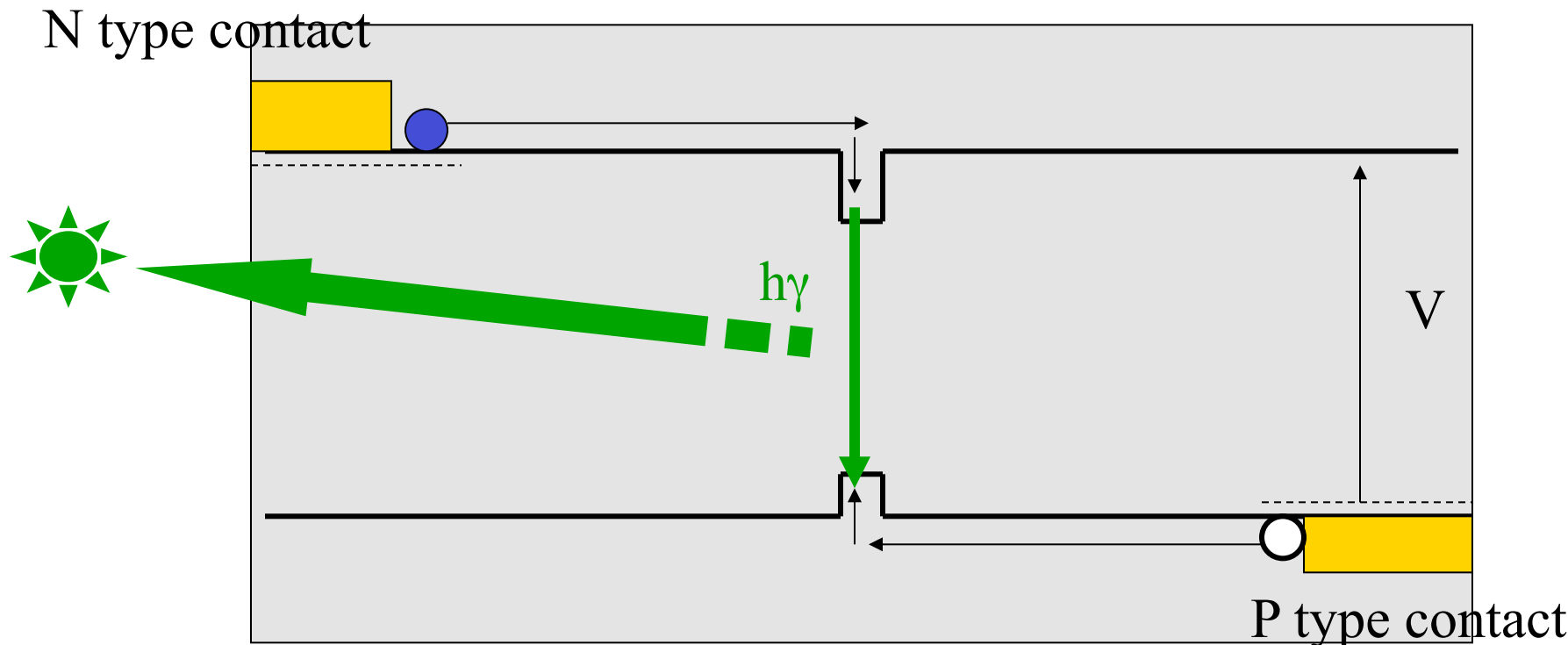
High efficiency !

LED

few mm



1 mm x 1mm



1 electron + 1 hole \Rightarrow 1 photon : Int. Quantum Eff. = 1

Photon escapes from LED: Extraction Eff. = 1

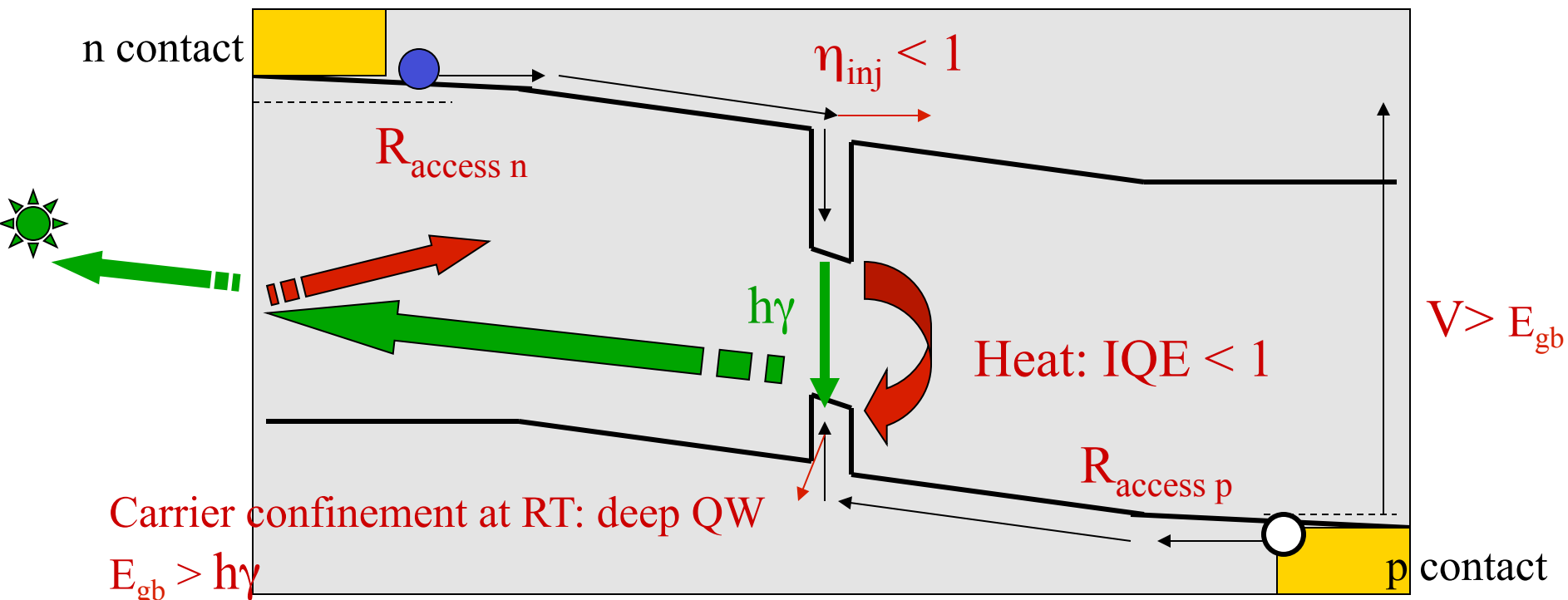
\Rightarrow EQE = 1

$V \sim E_{g \text{ barrier}}$

$$P_{\text{elec}} = V \times I \sim E_{g_b} \times I$$

$$P_{\text{opt}} = h\gamma \times \Phi = h\gamma \times I \Rightarrow \text{WPE} = P_{\text{opt}} / P_{\text{elec}} = h\gamma / E_{g_b} \sim 1$$





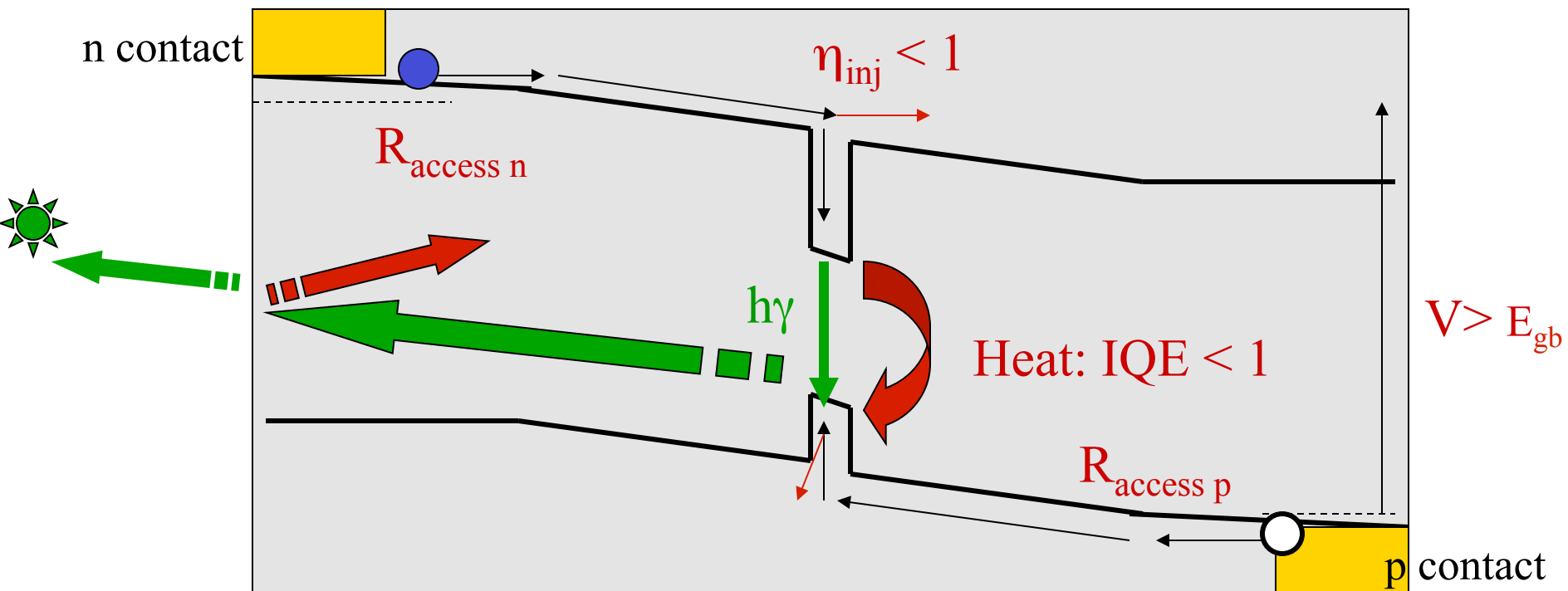
$$V \sim E_{g\ barrier} + R_{access} \times I$$

$$WPE = \underbrace{h\gamma / V}_{< 1} \times \underbrace{\eta_{inj} \times IQE \times EE}_{EQE < 1}$$

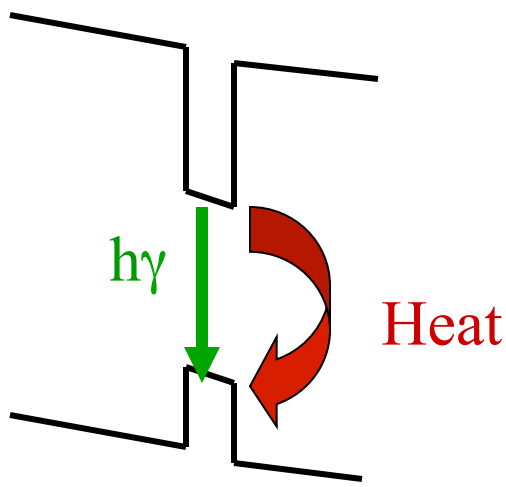


What can the epitaxy do to address these issues ?

- Almost everything ... if processing and design are OK
- Nothing if not !



OUTLINE



Radiative transitions described by a radiative time τ_R

Non radiative recombinations described by τ_{NR}

$$IQE = \frac{1/\tau_R}{1/\tau_R + 1/\tau_{NR}} = \frac{\tau_{NR}}{\tau_R + \tau_{NR}}$$

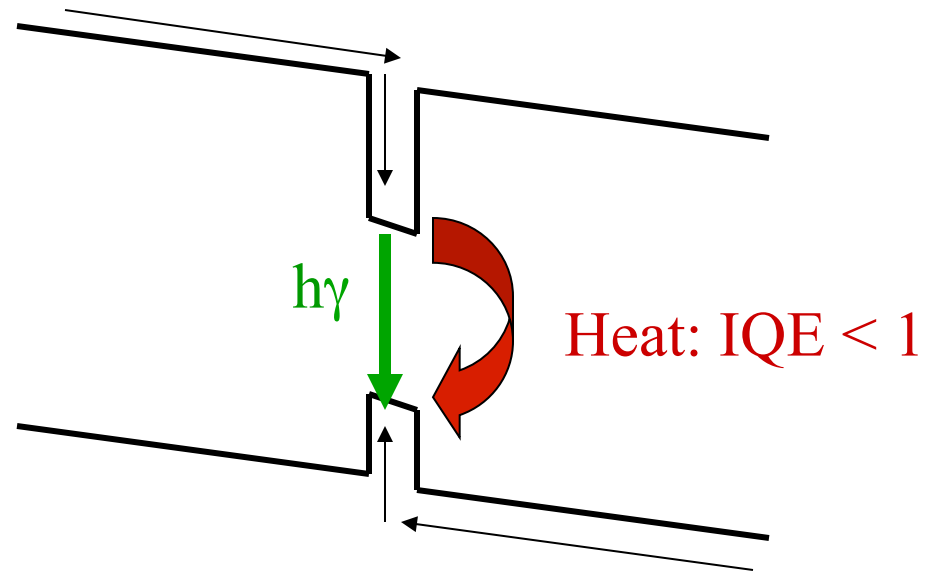
Minimize τ_R

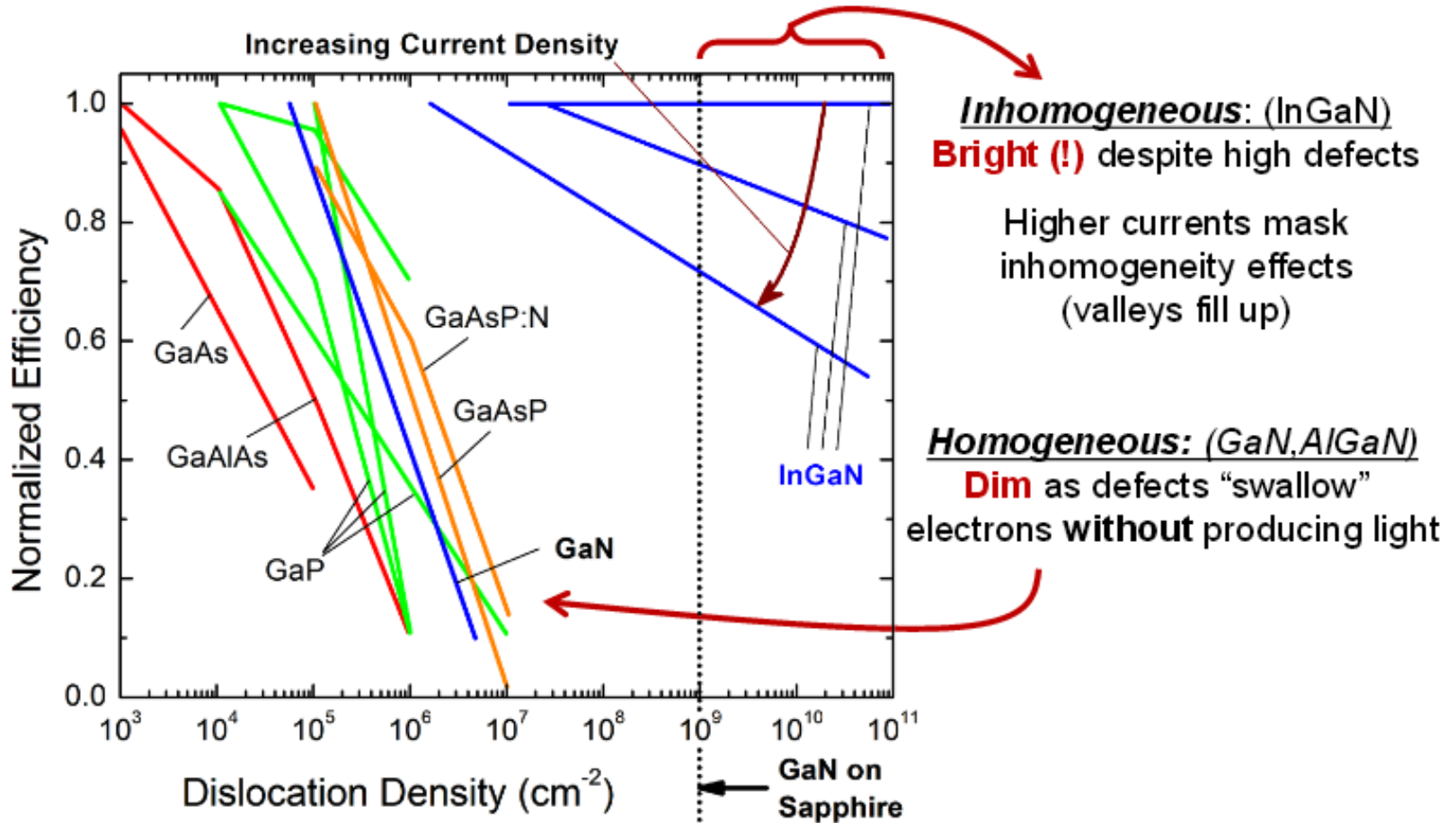
Maximize τ_{NR}

NB: some non linear phenomena and non exponential transients in particular at high injection. See later.

Non radiative recombinations

τ_{NR} decreases with defect density (point defects, dislocations)



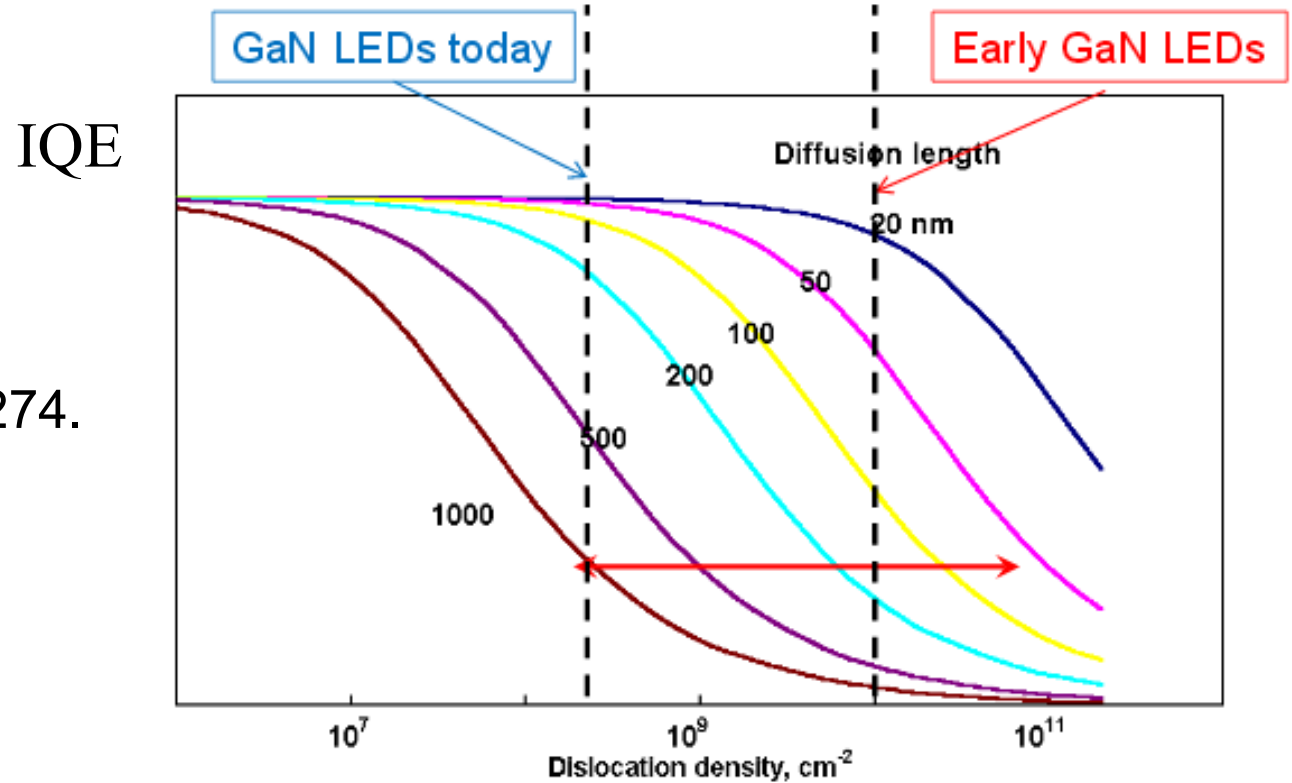


Nitrides more defect tolerant than other SC !!!

source: S. Nakamura, Nobel lecture

Dislocations and diffusion length

S. Speck and S.J. Rosner, Physica B274. 24 (1999)



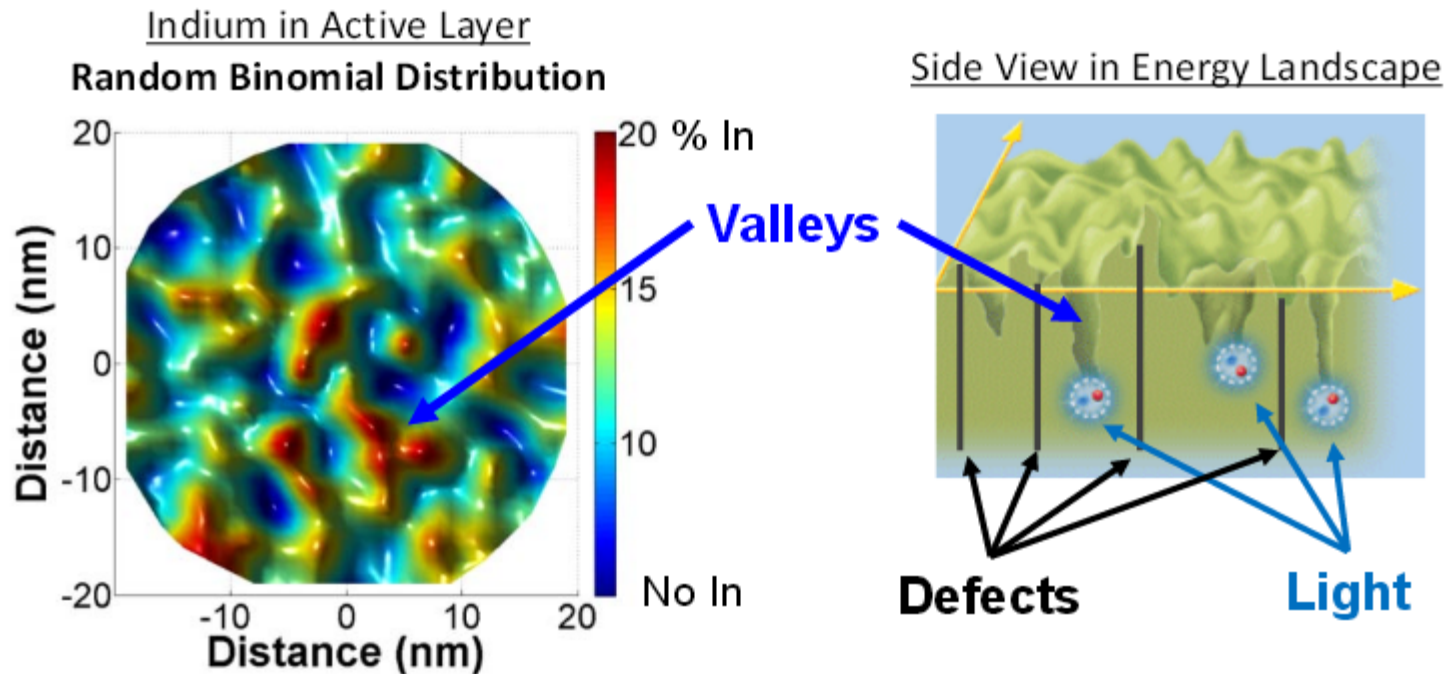
$$\text{Mean distance between dislocations} = DD^{-1/2}$$

EH pairs do not see dislocations if $L_{\text{dif}} < \text{disloc distance}$

$$DD = 10^8 \text{ cm}^{-2}, \text{ distance} = 1 \mu\text{m}$$

What can epitaxy do on diffusion length ?

Lateral potential fluctuations in QWs (In fluctuation) limit the diffusion length. QW epitaxy is crucial !

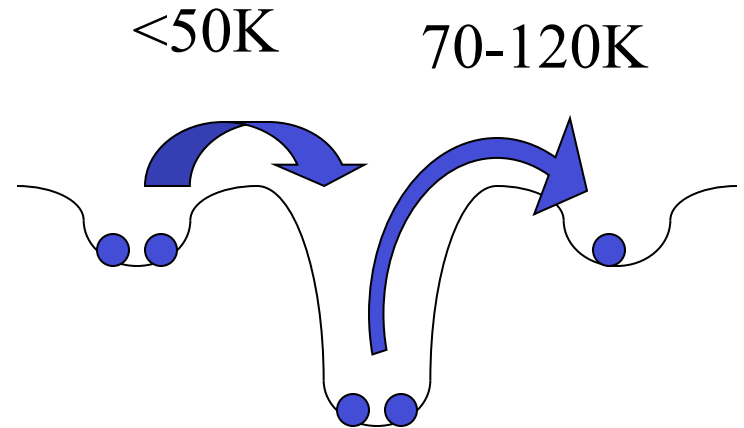
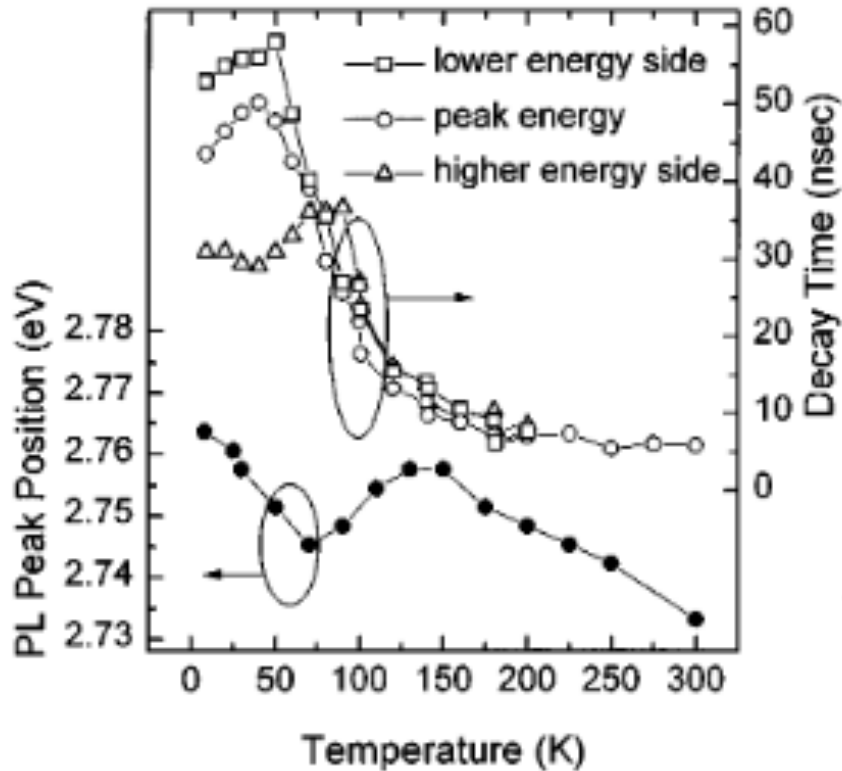


S. Nakamura, Nobel lecture. Chichibu, Nakamura et al., Appl. Phys. Lett., 69(1996) 4188; Nakamura, Science, 281(1998) 956.

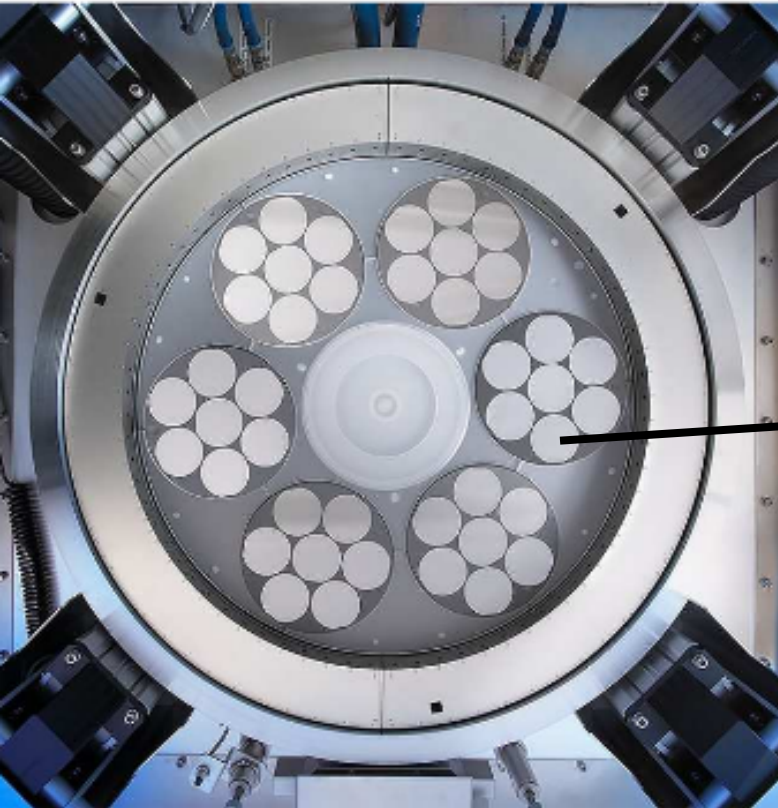
Many studies on In fluctuations, localization, S shape in PL versus T, In spinodal decomposition, In Quantum Dots ...

Patent issues: are InGaN LEDs based on Q Dots ?

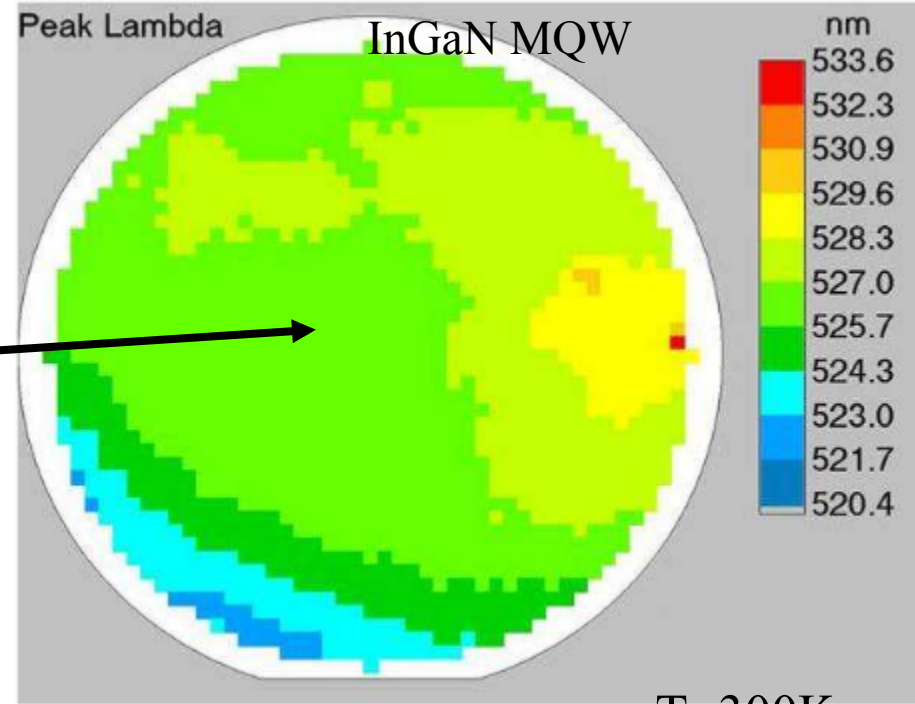
Exciton localisation and S-shape PL



Control on In content



42x2-inch Planetary Reactor



T=300K

Average wavelength = 527 nm

Standard deviation = 1,2 nm \Leftrightarrow 5 meV.

*Source INDOT (STREP 2008)
final activity report by Aixtron*

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InGaN now very uniform and high
IQE ! Different localization scale ?
Still an open question !!



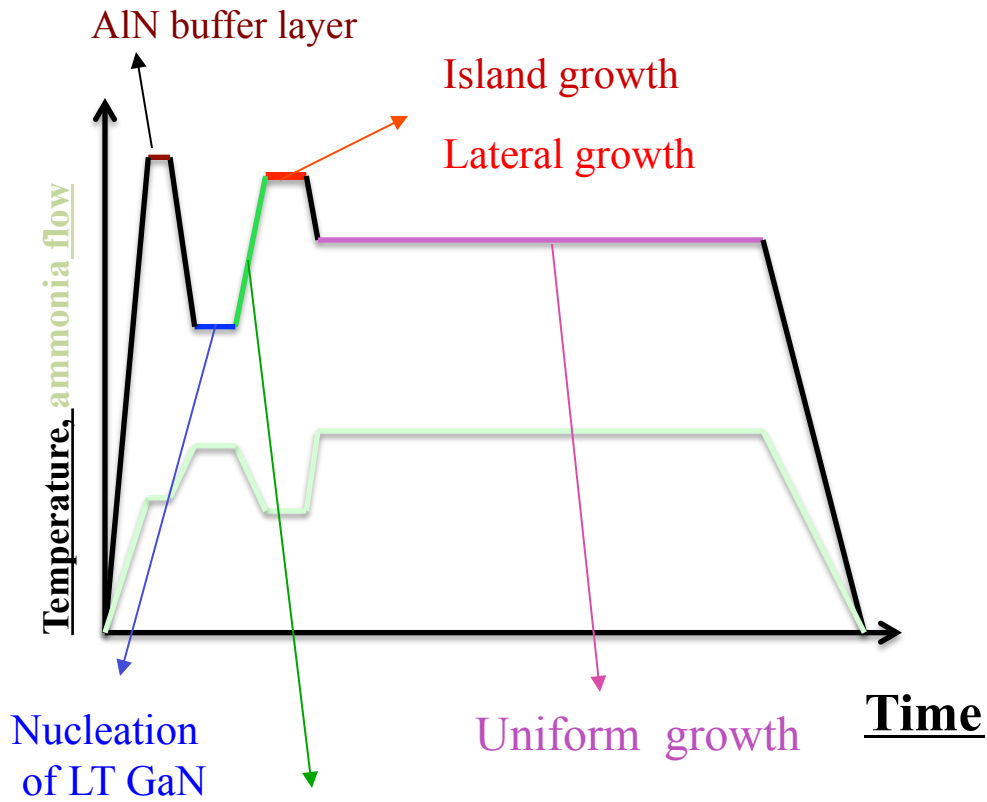
What can epitaxy do on the dislocation density ?

GaN substrates grown at equilibrium (2530 °C, 45 atm) or even close to, are extremely difficult to obtain : efforts by Unipress, Poland for 2 decades have led to cm^2 samples

- Heteroepitaxy is unavoidable
- No lattice matched substrate (sapphire lattice mismatch 16%, ...)
- Need for a transition layer (buffer)
- **Thousands of studies, papers, conferences on dislocation density reduction. Nobel prize !**
- High performance LED are currently fabricated on GaN with a DD $\sim 10^8 \text{ cm}^{-2}$ with IQE $>90 \%$.

Multi step growth on sapphire

Yoshida et al, Akasaki et al. , Hiramatsu et al. , Nakamura et al., 1986 to 2014



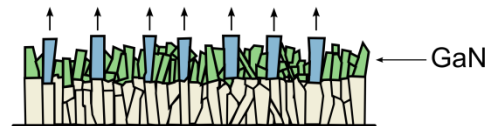
1) AlN buffer layer



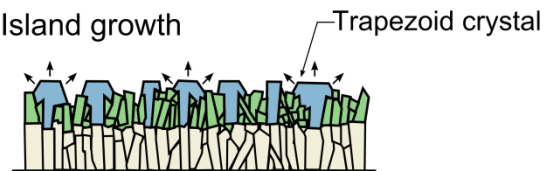
2) Nucleation of GaN



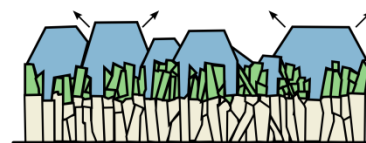
3) Geometric selection



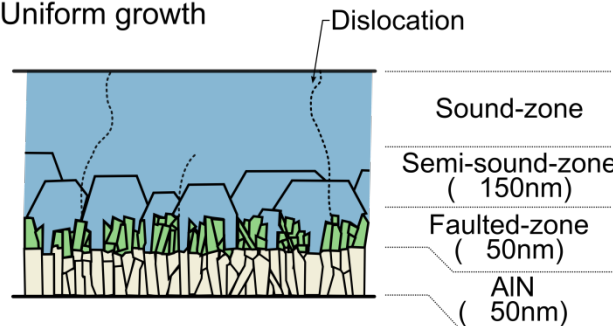
4) Island growth



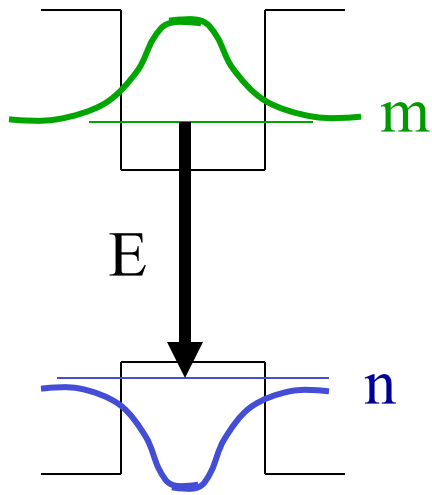
5) Lateral growth



6) Uniform growth



From B. Gil, GaN school 2015



Radiative transitions described by a radiative time $\tau_R \sim 1 / G_{mn}$

$$G_{mn} = \frac{e^2}{2h} \left| \vec{E} \cdot \vec{r}_{vc} \right|^2 \frac{m_r}{\hbar^2} \left| \langle nv | mc \rangle \right|^2 H(\hbar\omega - E_g - E_n^v - E_m^c) f_m^c(\hbar\omega) (1 - f_n^v(\hbar\omega))$$



Transition dipole



Wave function overlap



Energy conservation



Carriers in the QW : injection

$$G_{mn} = \frac{e^2}{2h} \left| \vec{E} \cdot \vec{r}_{vc} \right|^2 \frac{m_r}{\hbar^2} \left| \langle nv | mc \rangle \right|^2 H(\hbar\omega - E_g - E_n^v - E_m^c) f_m^c(\hbar\omega) (1 - f_n^v(\hbar\omega))$$

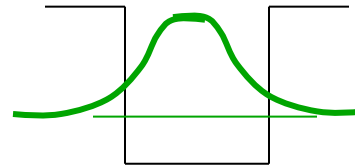


$$\left| \langle nv | mc \rangle \right| = \int \xi_{nv}(z) \xi_{mc}^*(z) dz$$

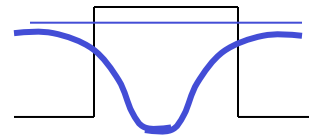
Material properties

Epitaxy (and design) can have an impact on transition

selection rules: remains limited for visible LEDs



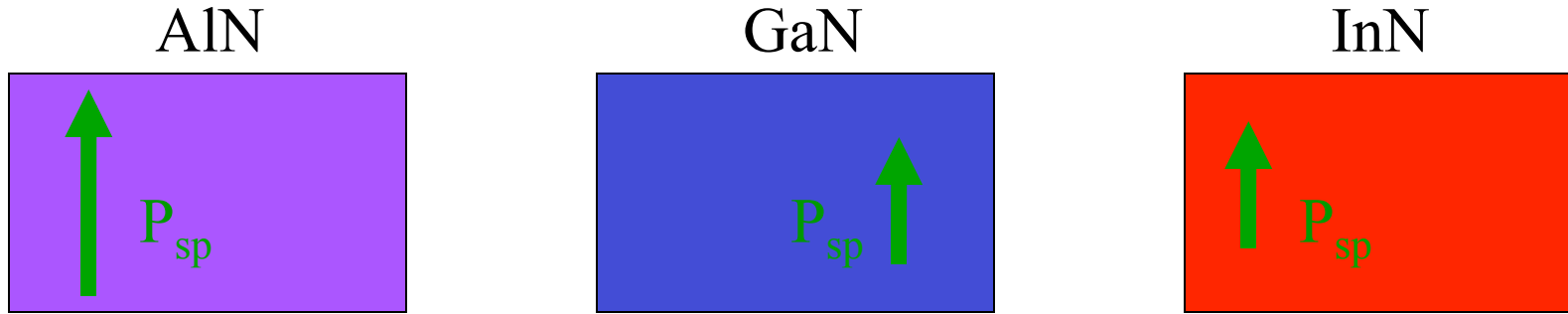
Envelope functions



Not a critical issue in "normal" semiconductors (GaAs) but very critical in GaN !

Polarization in wurzite nitrides

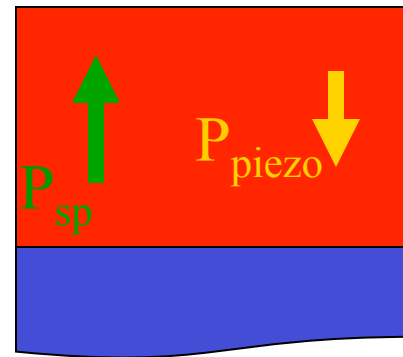
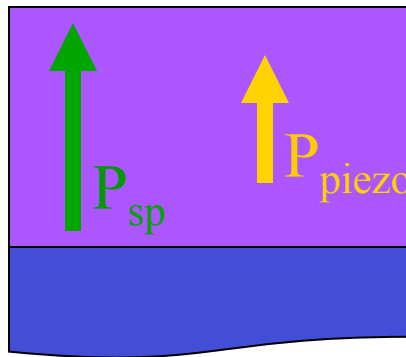
- Spontaneous polarisation :



	AlN	GaN	InN
P_{spont} (C/m ²)	-0.081	-0.029	-0.032

- Piezoelectric polarisation due to strain:

AlN (AlGaN)
in tension on
GaN



InN (InGaN) in
compression on
GaN

Polarization in heterostructures

$$\operatorname{div} \vec{F} = \frac{\rho}{\varepsilon} - \frac{1}{\varepsilon} \operatorname{div} \vec{P}$$

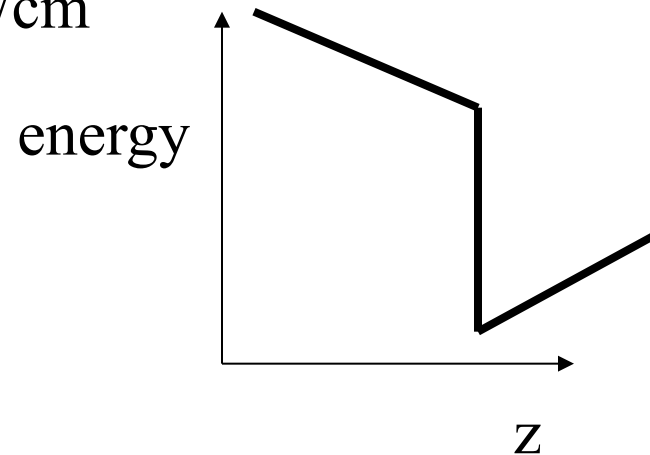
$$\frac{\partial F}{\partial z} = \frac{\rho(z)}{\varepsilon} - \frac{1}{\varepsilon} \frac{\partial P}{\partial z}$$

Across an interface along z :
$$\Delta F = -\frac{1}{\varepsilon_0 \varepsilon_r} \Delta P$$

$$\Delta P = P_{\text{AlN}} - P_{\text{GaN}} \approx 0.05\text{-}0.1 \text{ C/m}^2$$

$$\Delta F = F_{\text{AlN}} - F_{\text{GaN}} \approx \Delta P / \varepsilon_0 \varepsilon_r \approx 6\text{-}12 \text{ MV/cm}$$

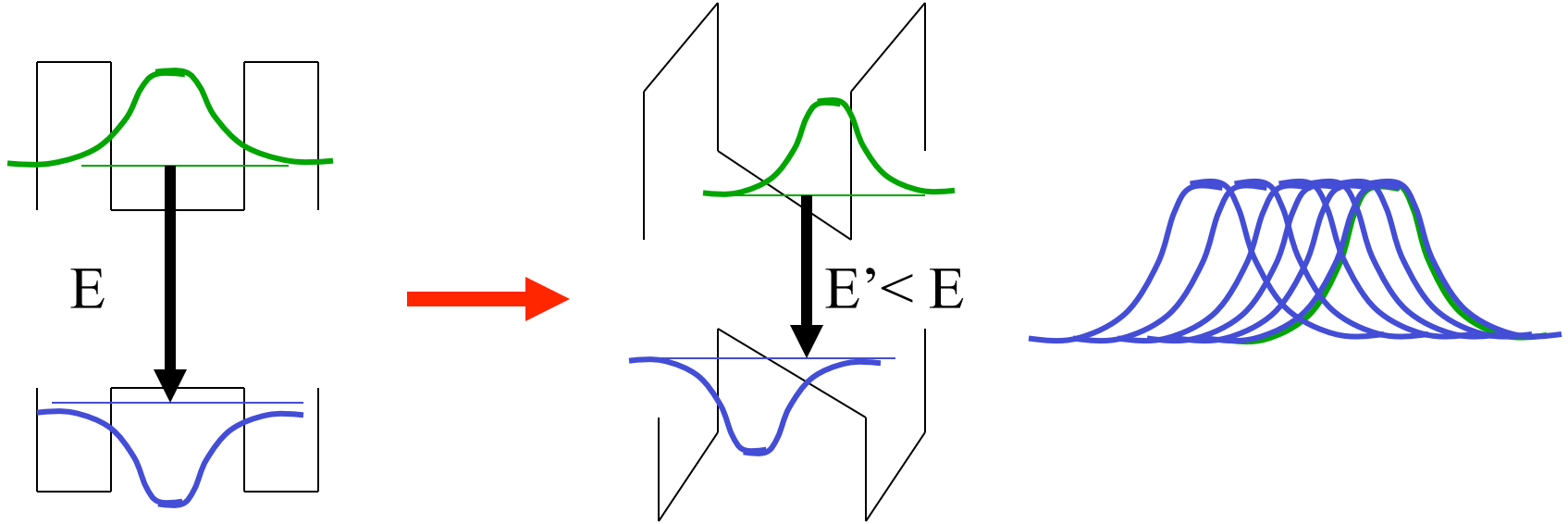
Enormous internal field
discontinuity at the interface !



Polarization in wurzite nitrides

In quantum wells:

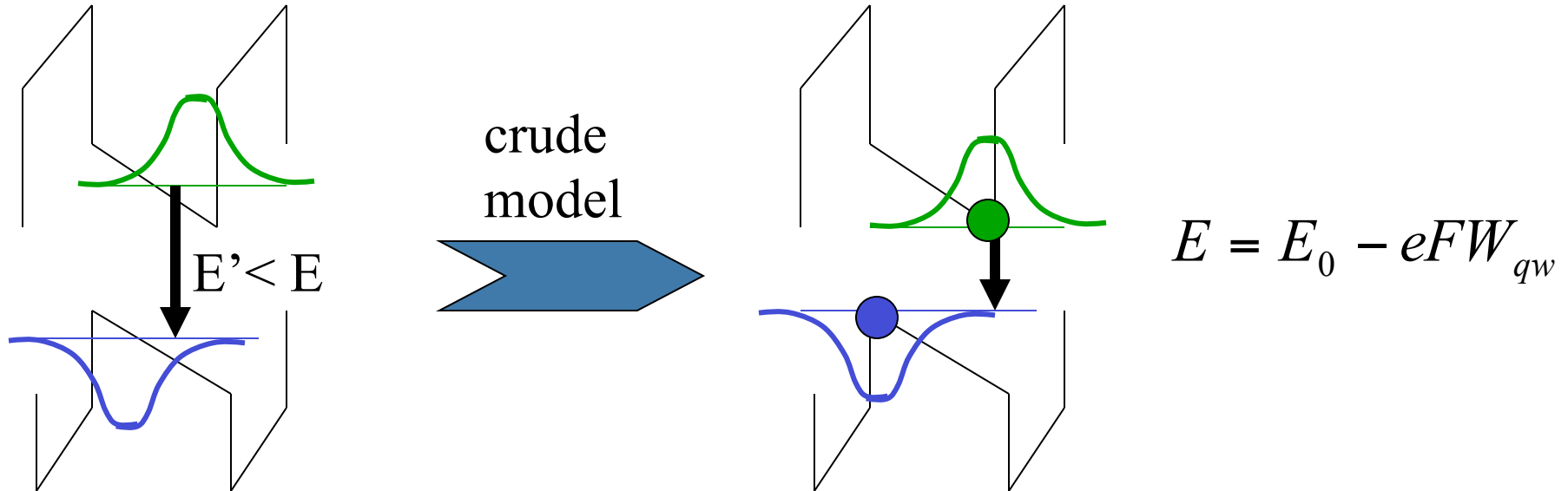
Quantum Confined Stark Effect



The energy redshifts and the wavefunction overlap decreases:

Polarization in wurzite nitrides

Quantum Confined Stark Effect



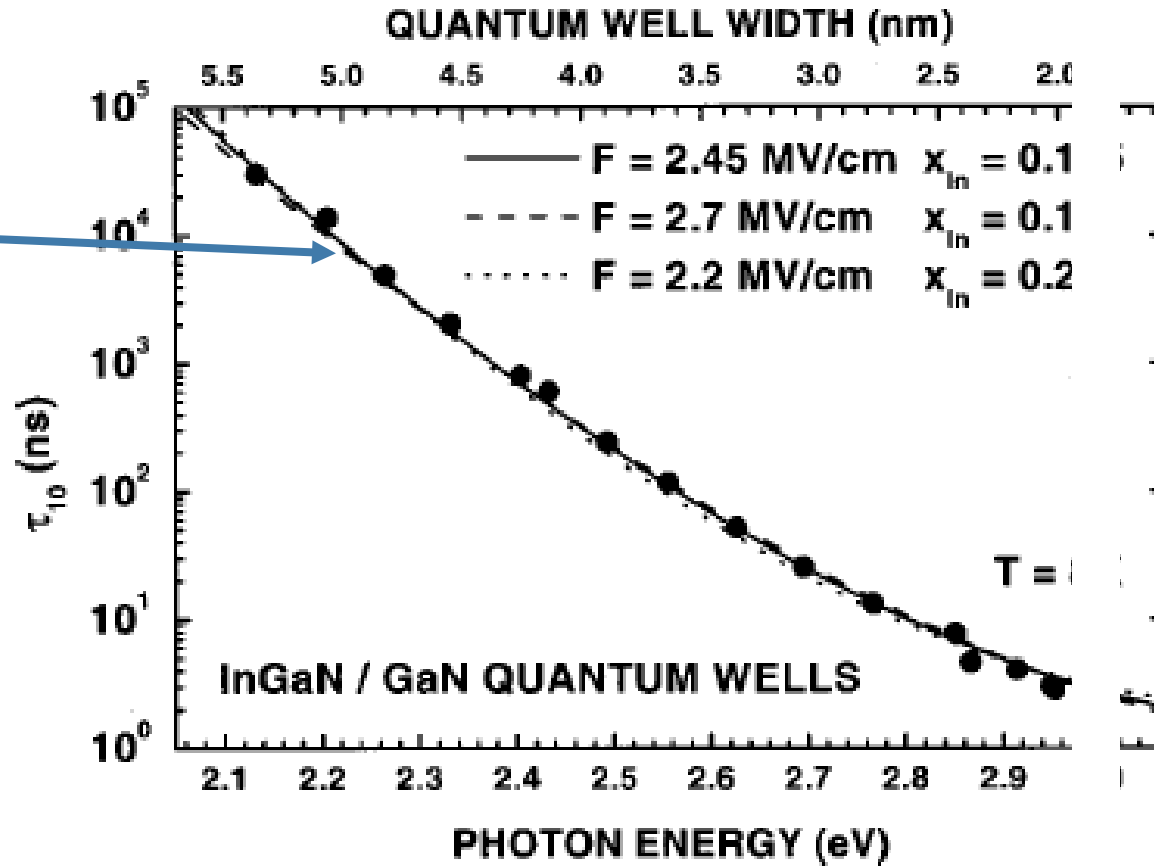
hole wavefunction decreases exponentially towards the electron wavefunctions or vice versa

$$|\langle nv | mc \rangle| = \int \xi_{nv}(z) \xi_{mc}^*(z) dz \approx e^{-W_{QW} / W_0}$$

Polarization in wurzite nitrides

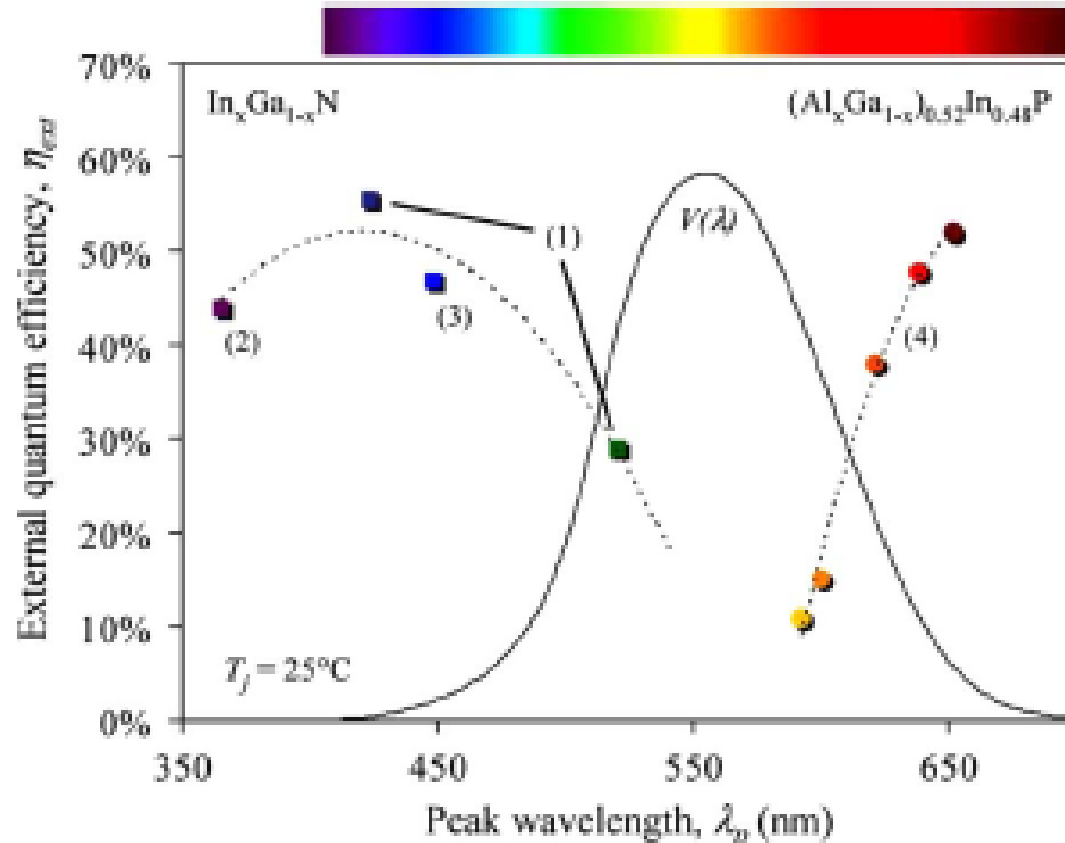
Radiative lifetime measured in InGaN OWs

Exponential decrease in large QWs

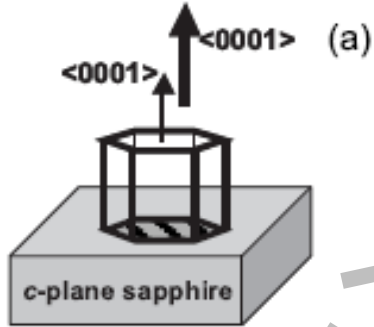


Polarization in wurzite nitrides

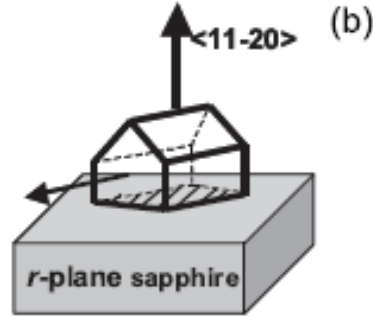
Stark effect is one of the reasons why green LEDs and lasers are less efficient than blue ones (green gap)



Non/semi polar materials

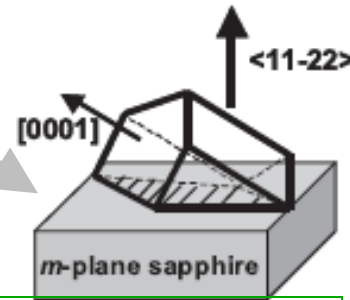


Growth along c :
polar



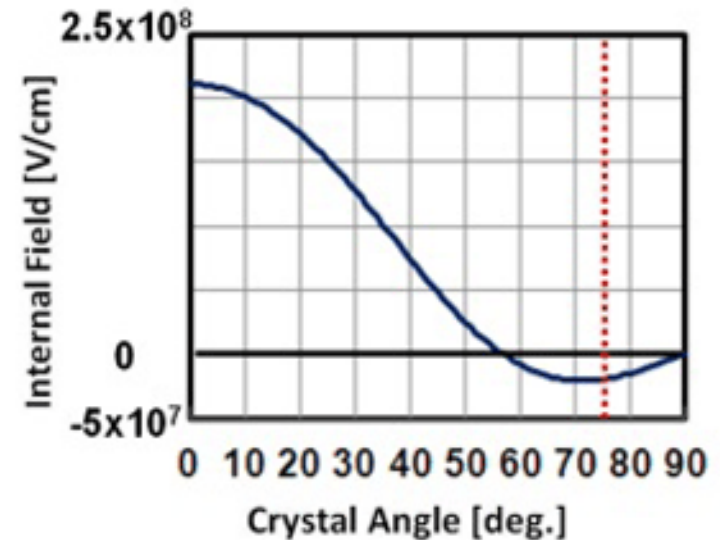
Growth $\perp c$: non polar

$$F = 0$$



Growth $\neq c$: semipolar

F weak



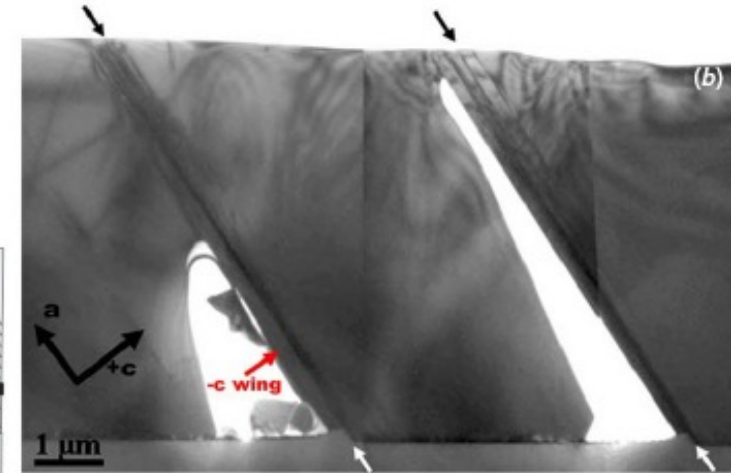
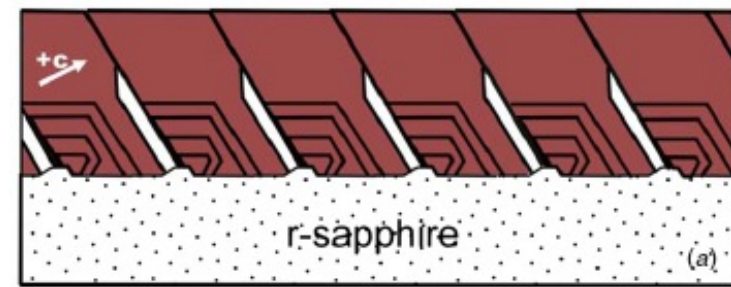
Non/semi polar materials

Approach	Result and problems	Solutions
Substrates with various cuts (Si, SiC, sapphire...)	<p>Large surface</p> <p>Dislocations ($>10^9 \text{ cm}^{-2}$) and stacking faults (10^5 cm^{-1})</p>	<p>Try new substrates.</p> <p>Optimize growth conditions</p>
GaN crystal grown along c and cut in oblique direction	<p>High quality material (Mitsubishi, Sumitomo)</p> <p>High performance LEDs and lasers (UCSB...)</p> <p>Small size</p>	<p>Increase initial thickness</p>
Localized epitaxy on inclined facets	<p>High quality</p> <p>Small size or problems of coalescence</p>	<p>Be smart to filter defects during lateral growth</p>

SP GaN

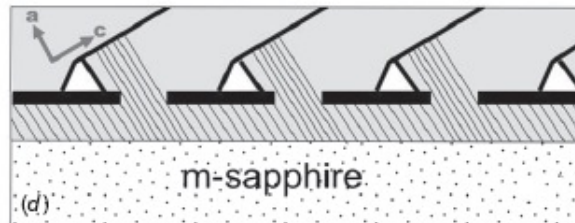
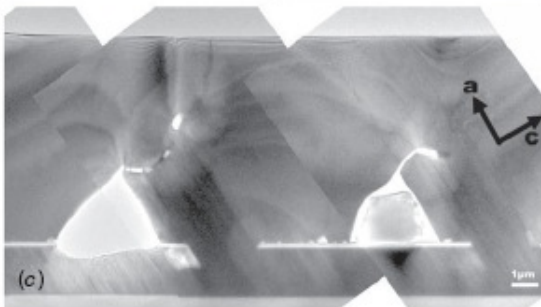
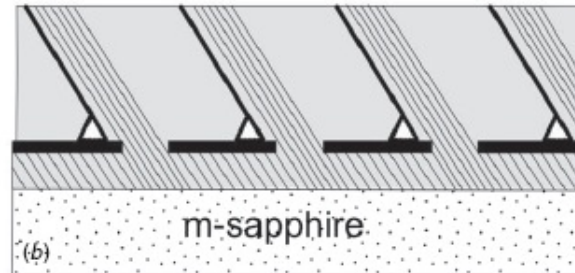
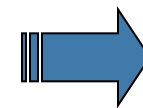
Localized + lateral epitaxy

Different steps with varied growth conditions



Start up project
from CRHEA

F. Tendille



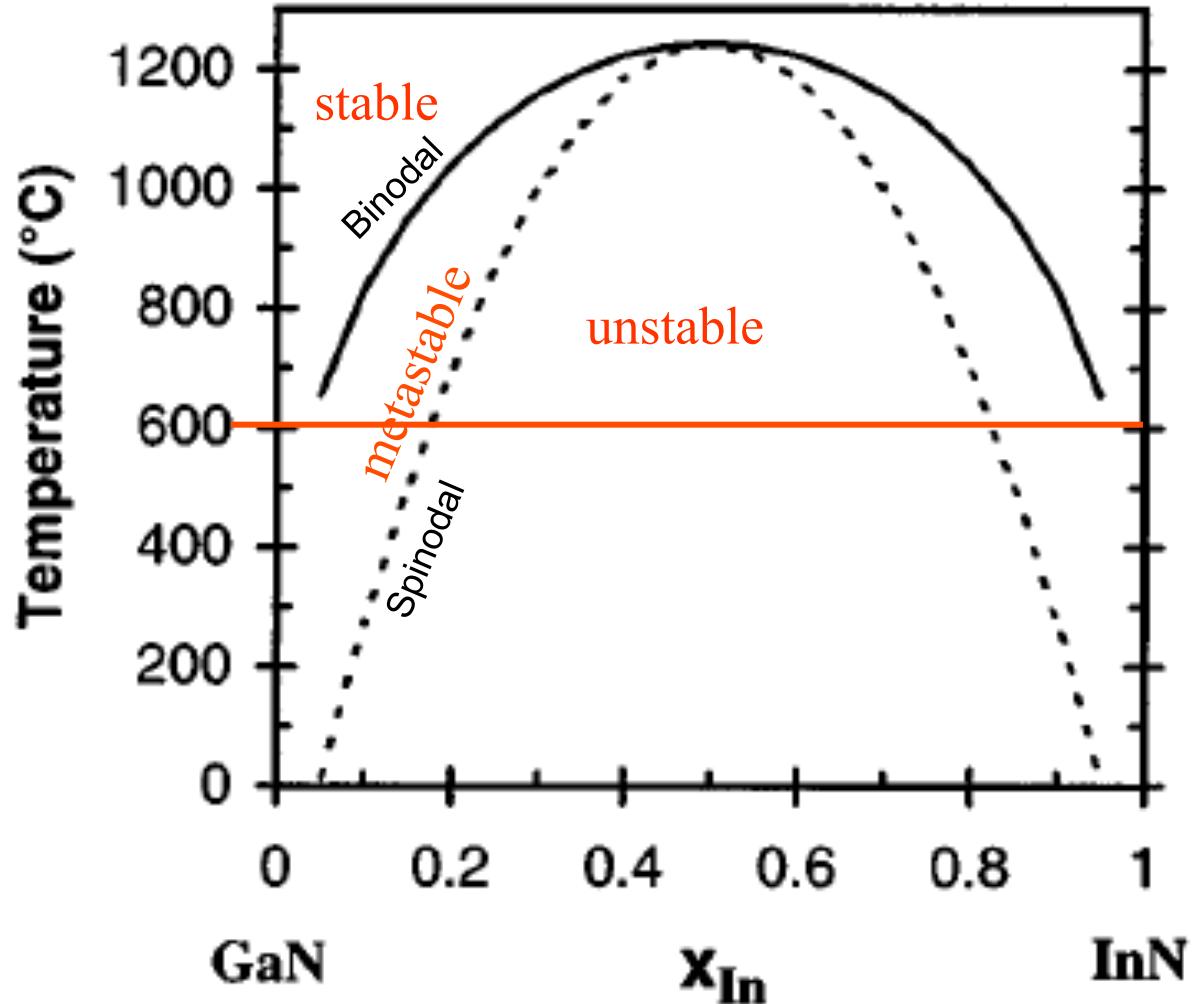
Epitaxy choice

- Non/semipolar material
 - Short τ_R is good if τ_{NR} remains long
- Polar material with thin QWs \Rightarrow large confinement energy \Rightarrow deeper QWs needed for the same transition energy \Rightarrow more Indium \Rightarrow new problems:
 - Strain, possible plastic relaxation, dislocations
 - Spinodal decomposition of InGaN (thermodynamic instability).

Decomposition of $\text{Ga}_{1-x}\text{In}_x\text{N}$

GaN and InN have very different atomic radii → Phase separation

Calculated GaInN alloy phase diagram

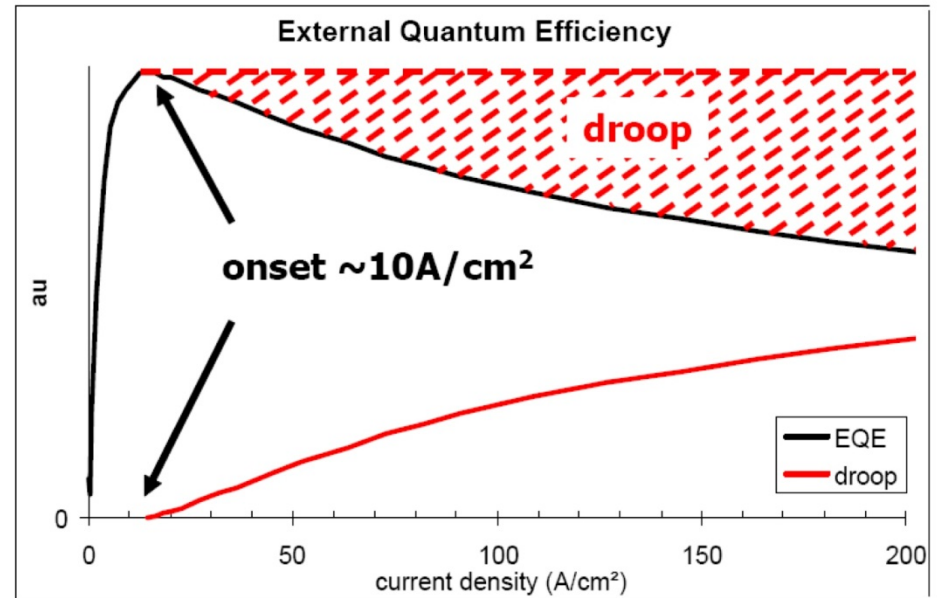
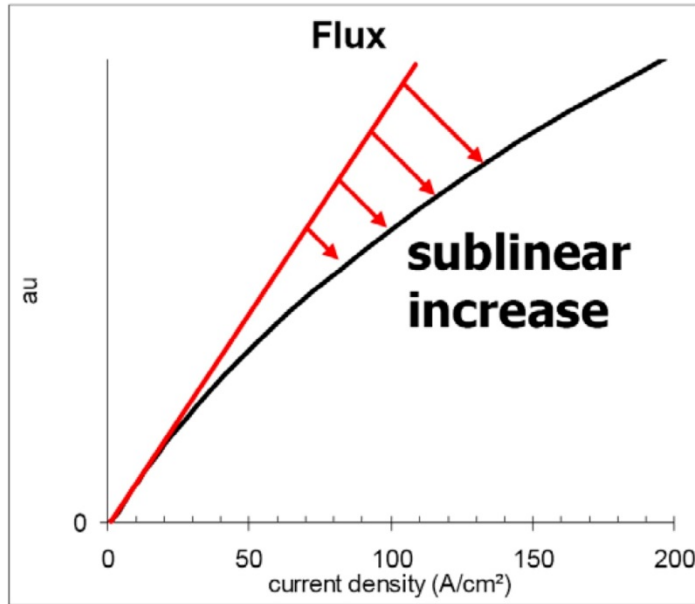


Very low solubility
of InN in GaN

Dynamics of phase
separation is
thermally activated :
InGaN can be grown
at low temperature

Ultimate problem : droop

Reduction of the quantum efficiency at high injection



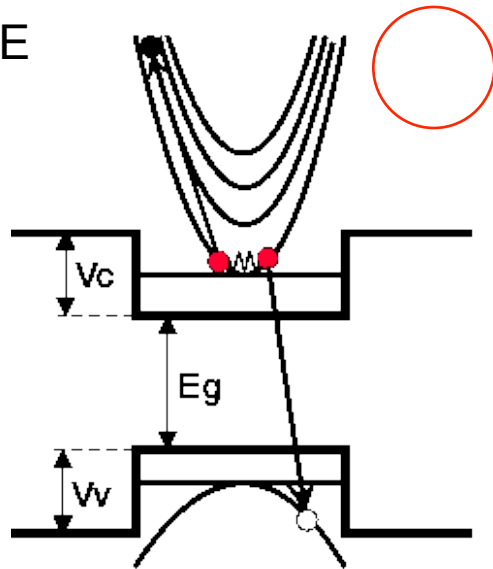
Origins of the efficiency droop

Auger recombination processes

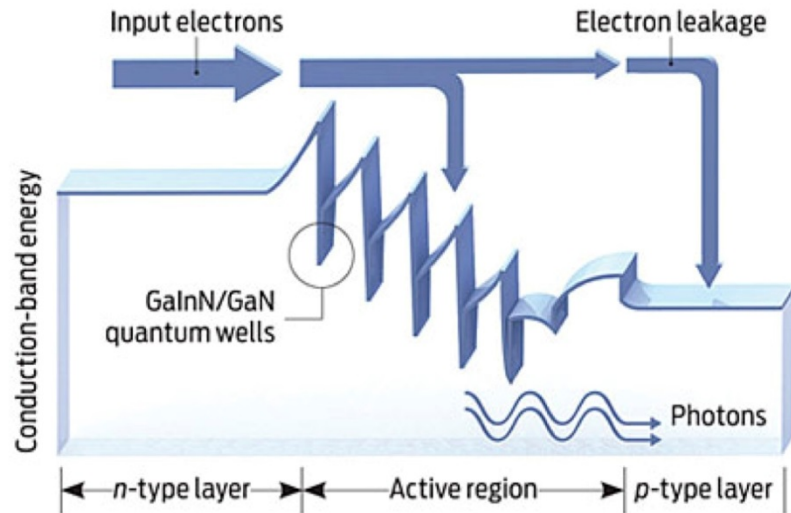
Carrier overshoot

$$\eta = \frac{\eta_{inj}BN^2}{AN + BN^2 + CN^3}$$

IQE



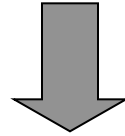
rate $\sim n^2p$



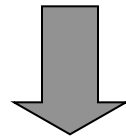
Solutions to the droop

Auger recombination processes

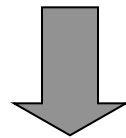
Non radiative rate $\sim C n^3$



Reduce n for a constant I

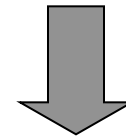


Increase well width

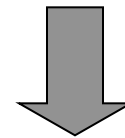


•QCSE

•Strain issues




Increase well number



Strain issues

Epitaxy !!

$$G_{mn} = \frac{e^2}{2h} \left| \overrightarrow{E} \cdot \overrightarrow{r}_{vc} \right|^2 \frac{m_r}{\hbar^2} \left| \langle nv | mc \rangle \right|^2 H(\hbar\omega - E_g - E_n^v - E_m^c) f_m^c(\hbar\omega) (1 - f_n^v(\hbar\omega))$$


Epitaxy (and design) can have an impact: remains limited for LEDs

Many epitaxial parameters:

- Polar / non polar
- Strain
- Barrier composition and thickness
- QW composition and thickness

Carrier injection

Large hole and electron densities in the QW

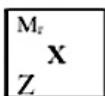
Doping

AlGaInN

Tableau périodique des éléments

1 (Ia)		2 (IIa)												13 (IIIa)	14 (IVa)	15 (Va)	16 (VIa)	17 (VIIa)	18 (VIIIa)
1,01 1 H		6,94 3 Li	9,01 4 Be											10,81 5 B	12,01 6 C	14,01 7 N	16,00 8 O	19,00 9 F	20,18 10 Ne
22,99 11 Na	24,31 12 Mg													26,98 13 Al	28,09 14 Si	30,97 15 P	32,07 16 S	35,45 17 Cl	39,95 18 Ar
39,10 19 K	40,08 20 Ca			44,96 21 Sc	47,88 22 Ti	50,94 23 V	52,00 24 Cr	54,94 25 Mn	55,85 26 Fe	58,93 27 Co	58,69 28 Ni	63,55 29 Cu	65,39 30 Zn	69,72 31 Ga	72,61 32 Ge	74,92 33 As	78,96 34 Se	79,90 35 Br	83,80 36 Kr
85,47 37 Rb	87,62 38 Sr			88,91 39 Y	91,22 40 Zr	92,91 41 Nb	95,94 42 Mo	Tc*	101,07 44 Ru	102,91 45 Rh	106,42 46 Pd	107,87 47 Ag	112,41 48 Cd	114,82 49 In	118,71 50 Sn	121,75 51 Sb	127,60 52 Te	126,90 53 I	131,29 54 Xe
132,91 55 Cs	137,33 56 Ba	57-70		174,97 71 Lu	178,49 72 Hf	180,95 73 Ta	183,85 74 W	186,21 75 Re	190,21 76 Os	192,22 77 Ir	195,08 78 Pt	196,97 79 Au	200,59 80 Hg	204,38 81 Tl	207,21 82 Pb	208,98 83 Bi	Po*	At*	Rn*
Fr*	Ra*	89-102		Lr*	Rf*	Db*	Sg*	Bh*	Hs*	Mt*	Uun*	Uuu*	Uub*						
87	88			103	104	105	106	107	108	109	110	111	112						

Masse atomique relative,
donnée avec deux décimales



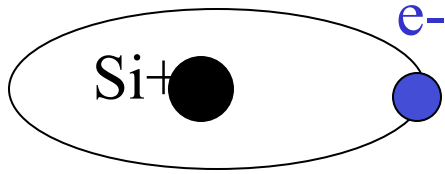
← Symbole de l'élément

Nombre atomique

138,92 57 La	140,12 58 Ce	140,91 59 Pr	144,24 60 Nd	Pm*	150,36 62 Sm	151,97 63 Eu	157,25 64 Gd	158,93 65 Tb	162,50 66 Dy	164,93 67 Ho	167,26 68 Er	168,93 69 Tm	173,04 70 Yb
Ac*	232,04 90 Th	231,04 91 Pa	238,03 92 U	Np*	Pu*	Am*	Cm*	Bk*	Cf*	Es*	Fm*	Md*	No*
89	90	91	92	93	94	95	96	97	98	99	100	101	102

* : Eléments n'ayant pas de nucléide (isotope) de durée de vie suffisamment longue et n'ayant donc pas une composition terrestre caractéristique.

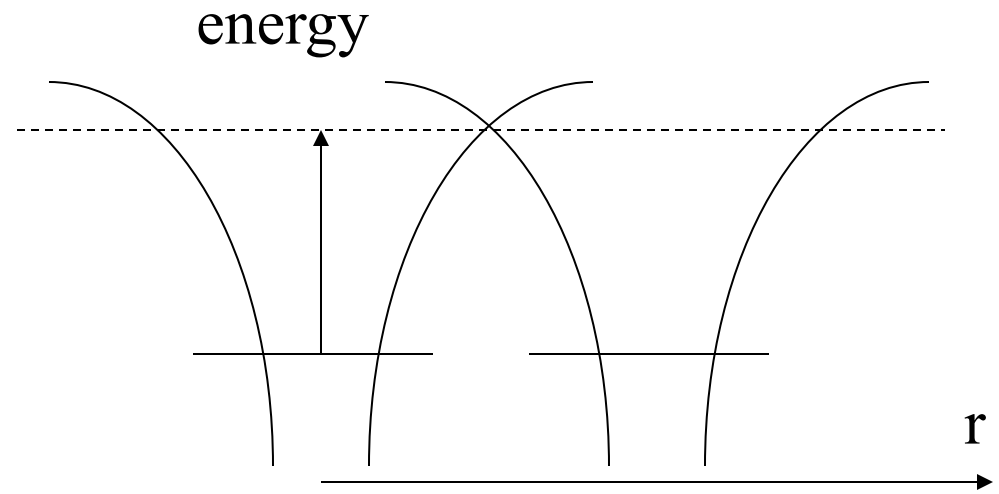
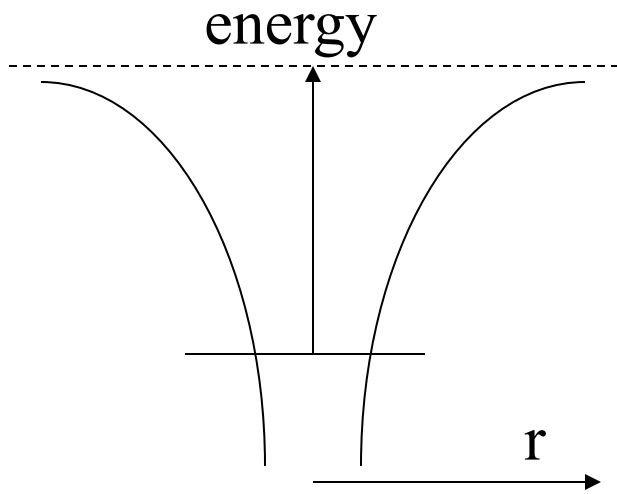
Donors



$$E = \frac{m_e}{m_0} \frac{1}{\epsilon_r^2} R_y$$

Large donor energies are expected in nitrides (37 meV)

$$1/\mu = 1/m_e + 1/m_{Si} \approx 1/m_e$$



Donor energy renormalized at high concentration

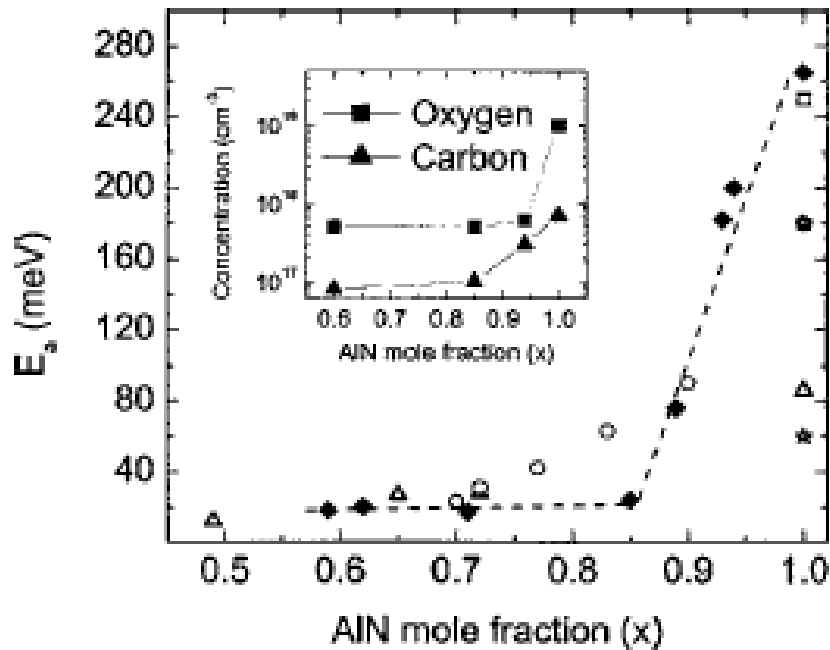
$$E = E_0 - \beta n^{1/3} \text{ with } \beta = 10^{-8} \text{ eV/cm}$$

Donors in GaN - AlGaN

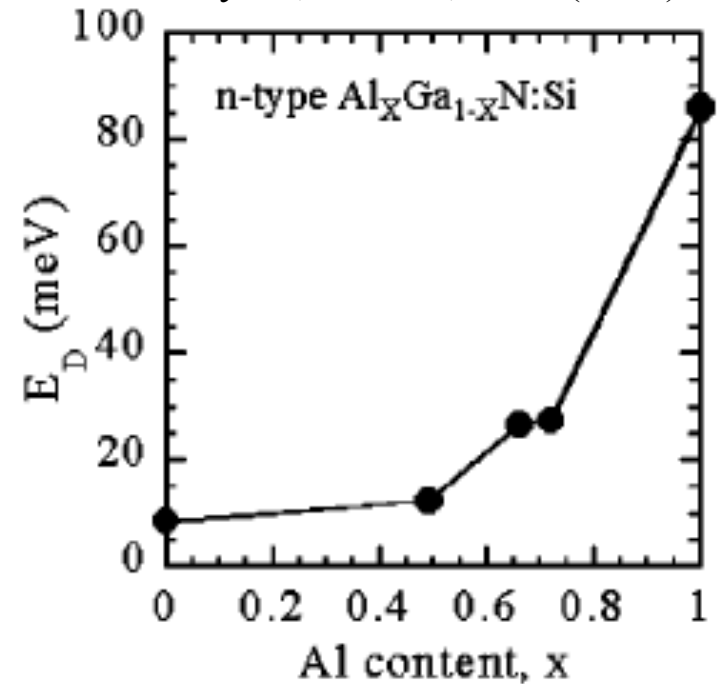
O : shallow donor in GaN (26 meV) but deep level in AlGaN

Si: shallow donor in GaN (25 meV), deeper in AlGaN (250 meV)

B. Borisov, APL 87,132106 (2005)

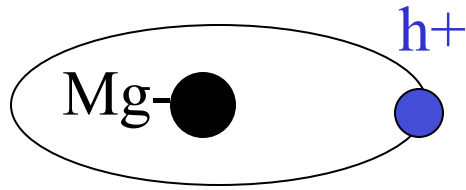


Taniyasu, APL 81, 1255 (2002)



Conclusion: n-doping by Si (Ge for reducing strain, not used for LEDs)

Acceptors: Mg



$$E = \frac{m_e}{m_0} \frac{1}{\epsilon_r^2} R_y$$

Very large acceptor binding energies are expected in nitrides (168 meV with $m_h=1$): not hydrogenoid !

$$1/\mu = 1/m_h + 1/m_{Mg} \approx 1/m_h$$

$$E_{Mg} = 220 \text{ meV}$$

⇒ Low ionization ratio

⇒ Large Mg densities necessary: $5 \times 10^{19} \text{ cm}^{-3}$ for $p = 5 \times 10^{17} \text{ cm}^{-3}$

⇒ Large energy renormalization:

$$E = E_0 - \beta n^{1/3} = 180 \text{ meV} \quad (\beta = 10^{-8} \text{ eVcm})$$

Acceptors: alternatives to Mg ?

Time-resolved spectroscopy of Zn- and Cd-doped GaN

P. Bergman, Gao Ying,^{a)} B. Monemar, and P. O. Holtz

Department of Physics and Measurement Technology, Linköping University, S-581 83 Linköping, Sweden

(Received 27 October 1986; accepted for publication 22 December 1986)

Journal of Applied Physics 61, 4589 (1987)

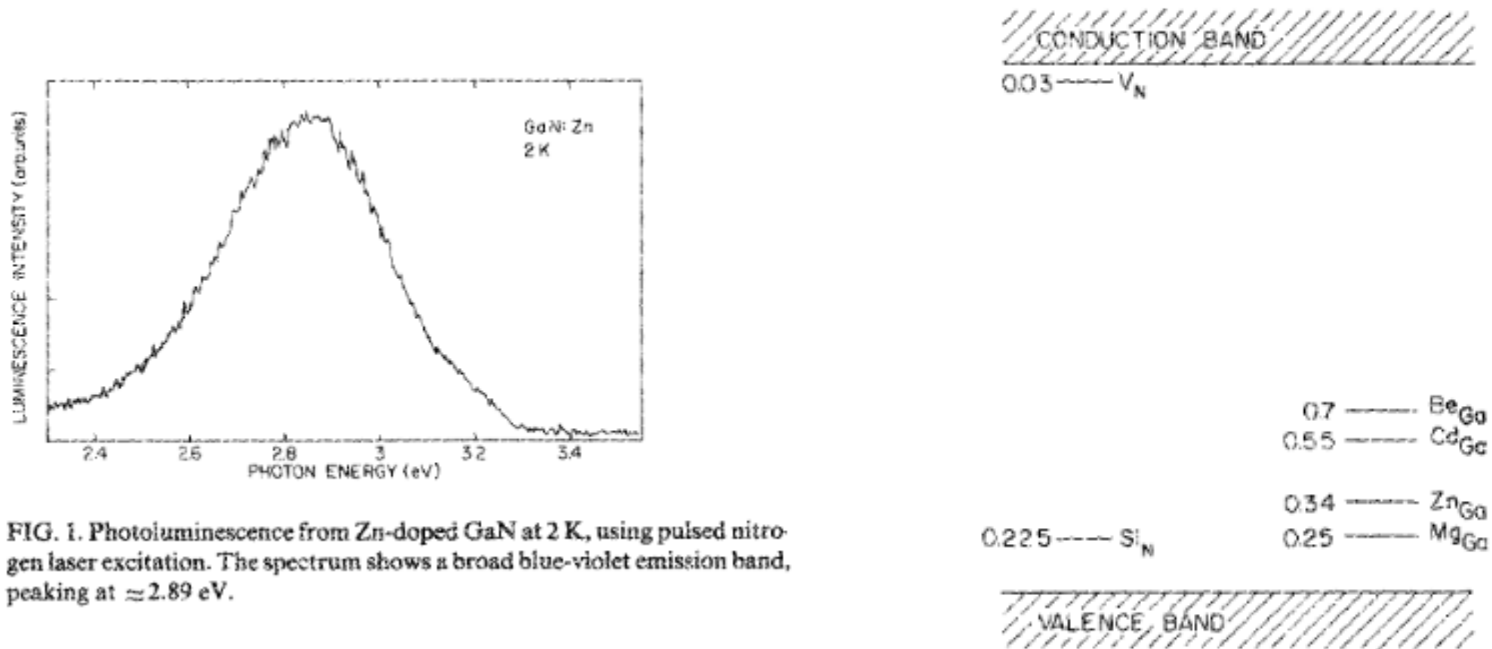


FIG. 1. Photoluminescence from Zn-doped GaN at 2 K, using pulsed nitrogen laser excitation. The spectrum shows a broad blue-violet emission band, peaking at ≈ 2.89 eV.

Conclusion: p-doping by Mg

Mg acceptor: other problems

Thermodynamic ionised defect formation energy and compensation mechanism

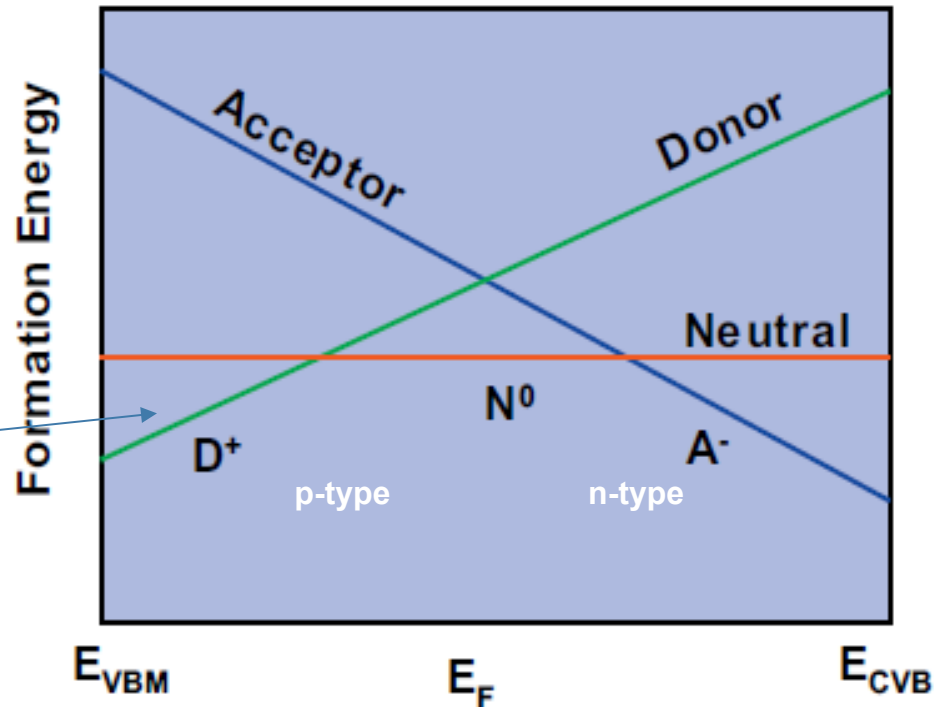
Donor case

$$E_f(d, q) = E_t(d) - E_t(0) + \mu_{i_d} + q E_{\text{Fermi}}$$

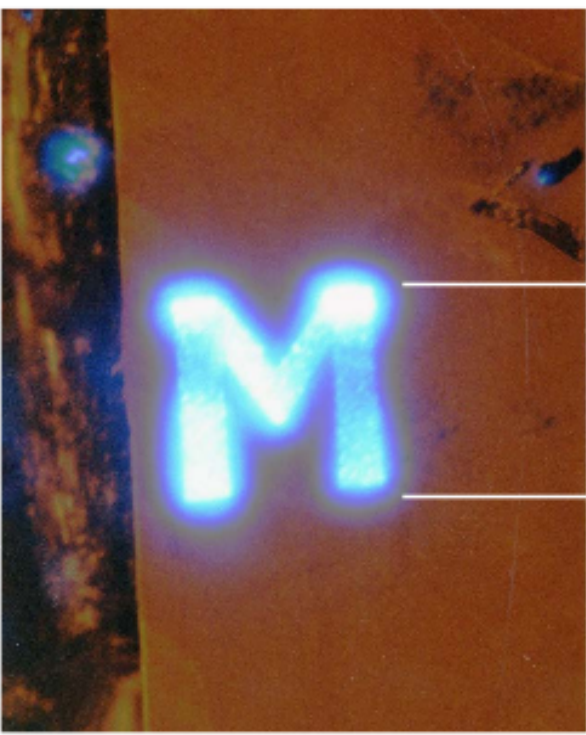
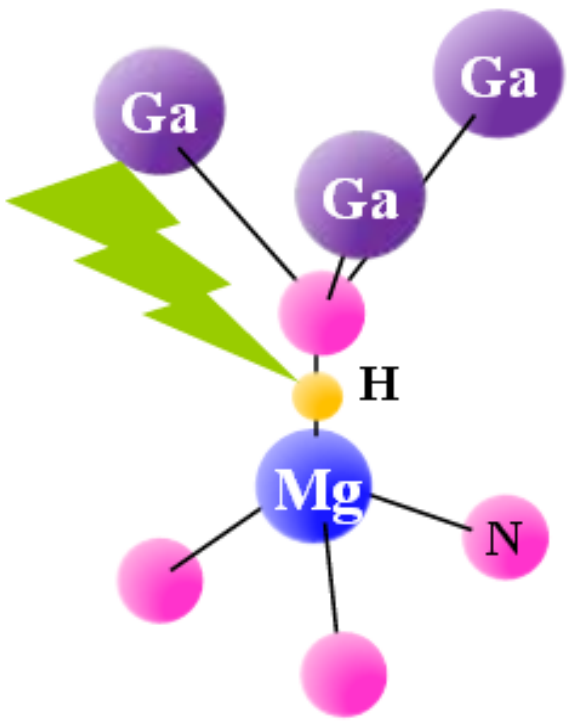
Acceptor case

$$E_f(d, q) = E_t(a) - E_t(0) + \mu_{i_a} - q E_{\text{Fermi}}$$

In p type materials, the Ga/Mg substitution becomes more difficult: other insertion sites where Mg is not active



The solution: with H, Mg is not active during epitaxy, better Mg incorporation in Ga substitution. H is eliminated afterwards (LEEBI or annealing)



50 μm

H. Amano
et al., JJAP
28(1989)L2112.



1992 Thermal annealing

S. Nakamura

et al., JJAP 31(1992)1258.

Electron and hole densities in GaN

Si doping:

$$n=10^{17}-10^{20} \text{ cm}^{-3}$$

Mg doping

$P \sim 5 \times 10^{17} \text{ cm}^{-3}$ for $\text{Mg} = 5 \times 10^{19} \text{ cm}^{-3}$ MOCVD

$P \sim 10^{18} \text{ cm}^{-3}$ MBE : less compensation as less thermodynamic because lower temperature (which is good for InGaN QWs), less H_2

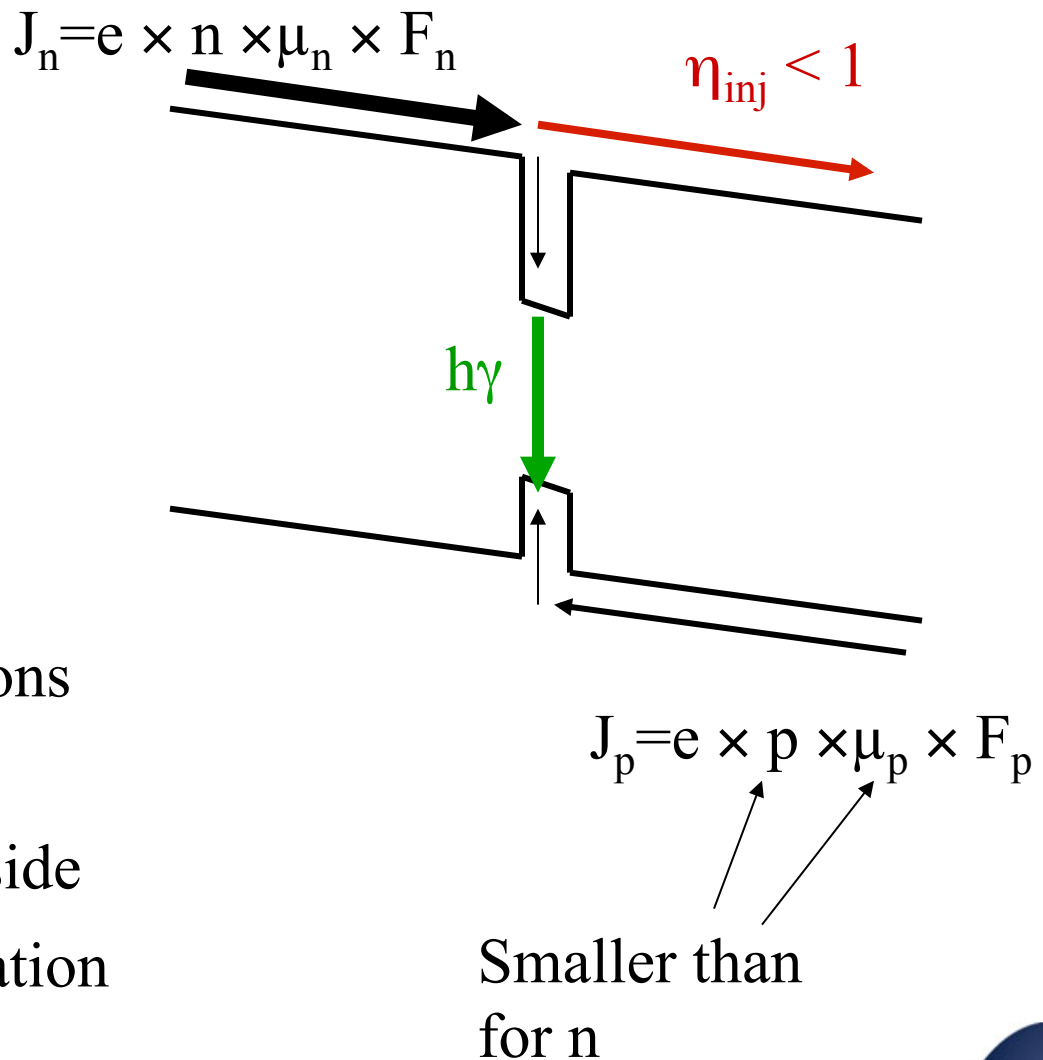
Carrier injection

Under high injection, the carrier densities close to the QW are proportional to the densities in the doped layers: $J=e \times n \times \mu \times F$

In the barrier: $J_n > J_p$

In the QW, if recombinations are radiative only, $J_n = J_p$

⇒ Electrons injected in p side with non useful recombination

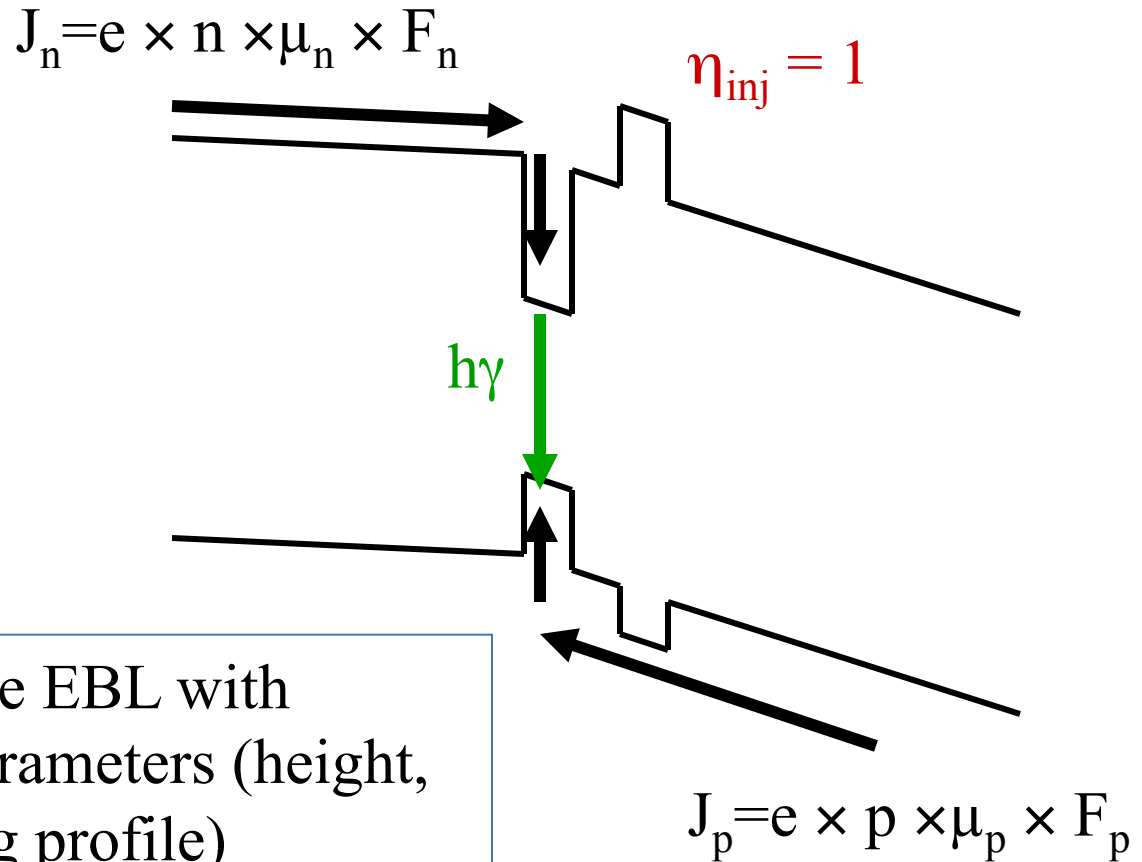


Carrier injection

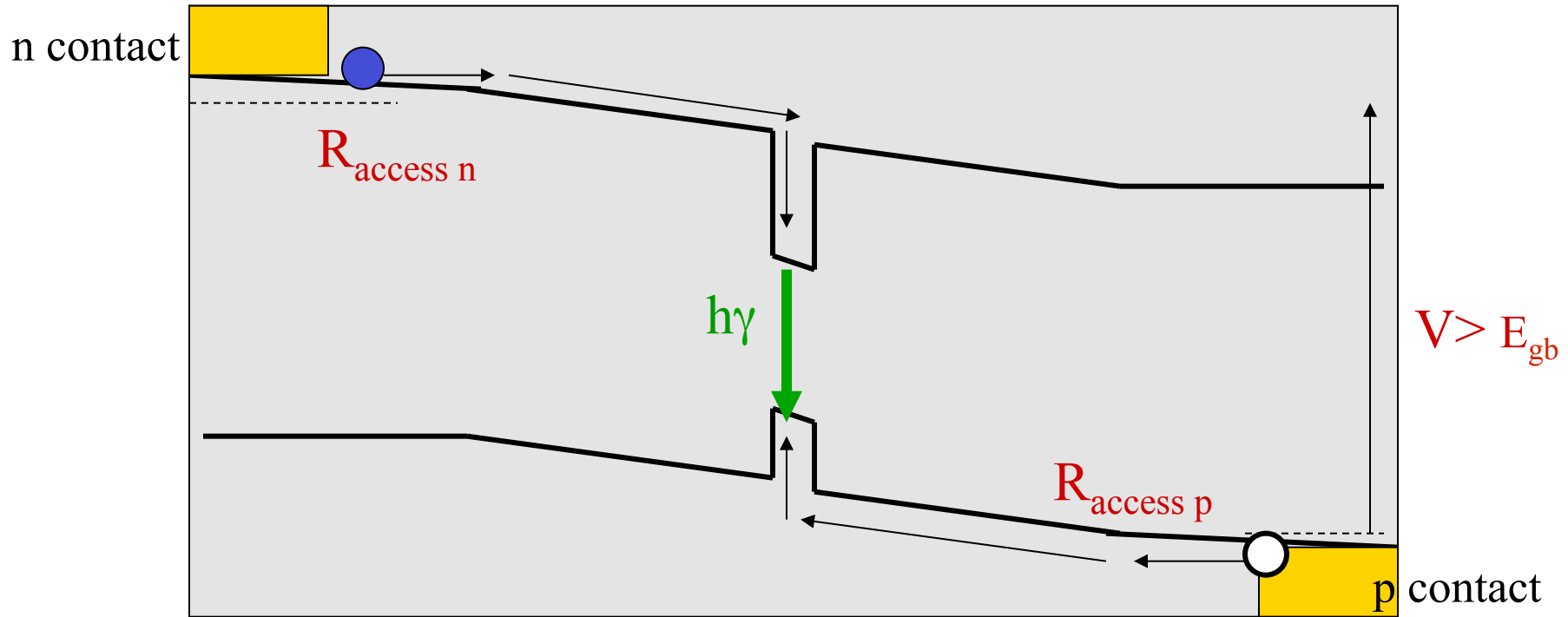
Electrons are blocked (EBL), accumulate in the QW. The field redistribute, is larger on p side, the hole current increases. The electron current decreases

Finally, $J_n = J_p$ in the whole structure

Epitaxy of the EBL with optimized parameters (height, width, doping profile)



Access resistance



n type contact: $\rho \sim 10^{-5} \Omega\text{cm}^2$

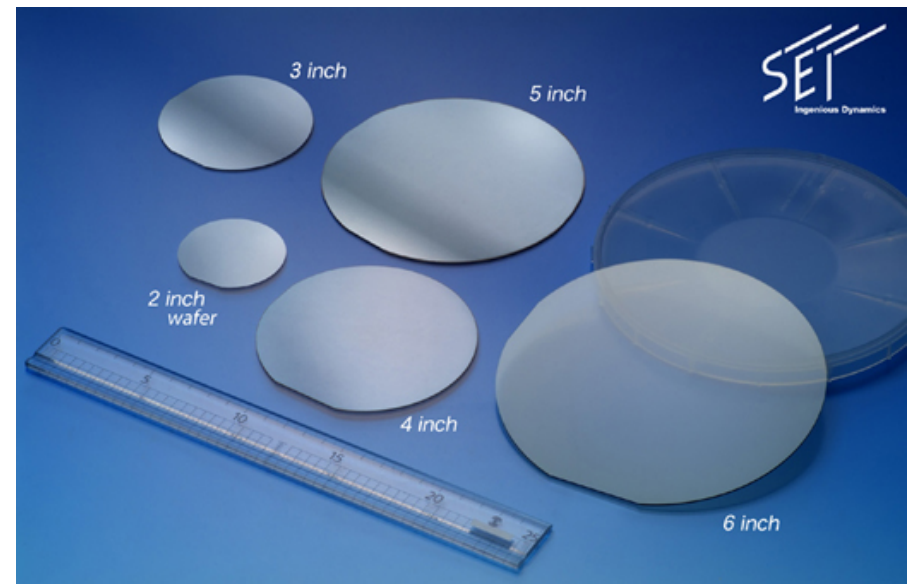
p type contact: $\rho \sim 10^{-3} \Omega\text{cm}^2$ (epitaxy optimized close to the surface): @ 100 Acm^2 , $\Delta V=0.1 \text{ V}$

Crucial for the WPE

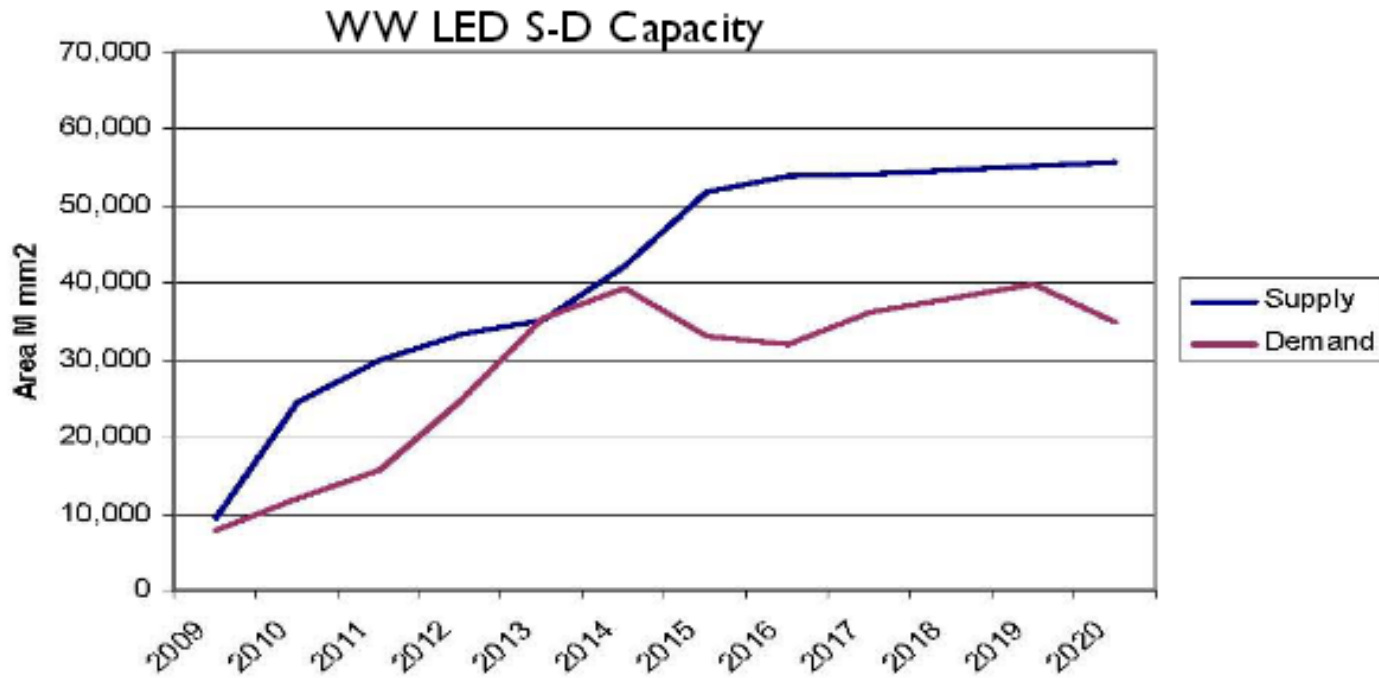
Substrates for LEDs

All major players on sapphire:

- The MOVPE process is now well mastered
- Transparent but is removed sometimes (thermal, backside contact)
- Price is decreasing and size increasing

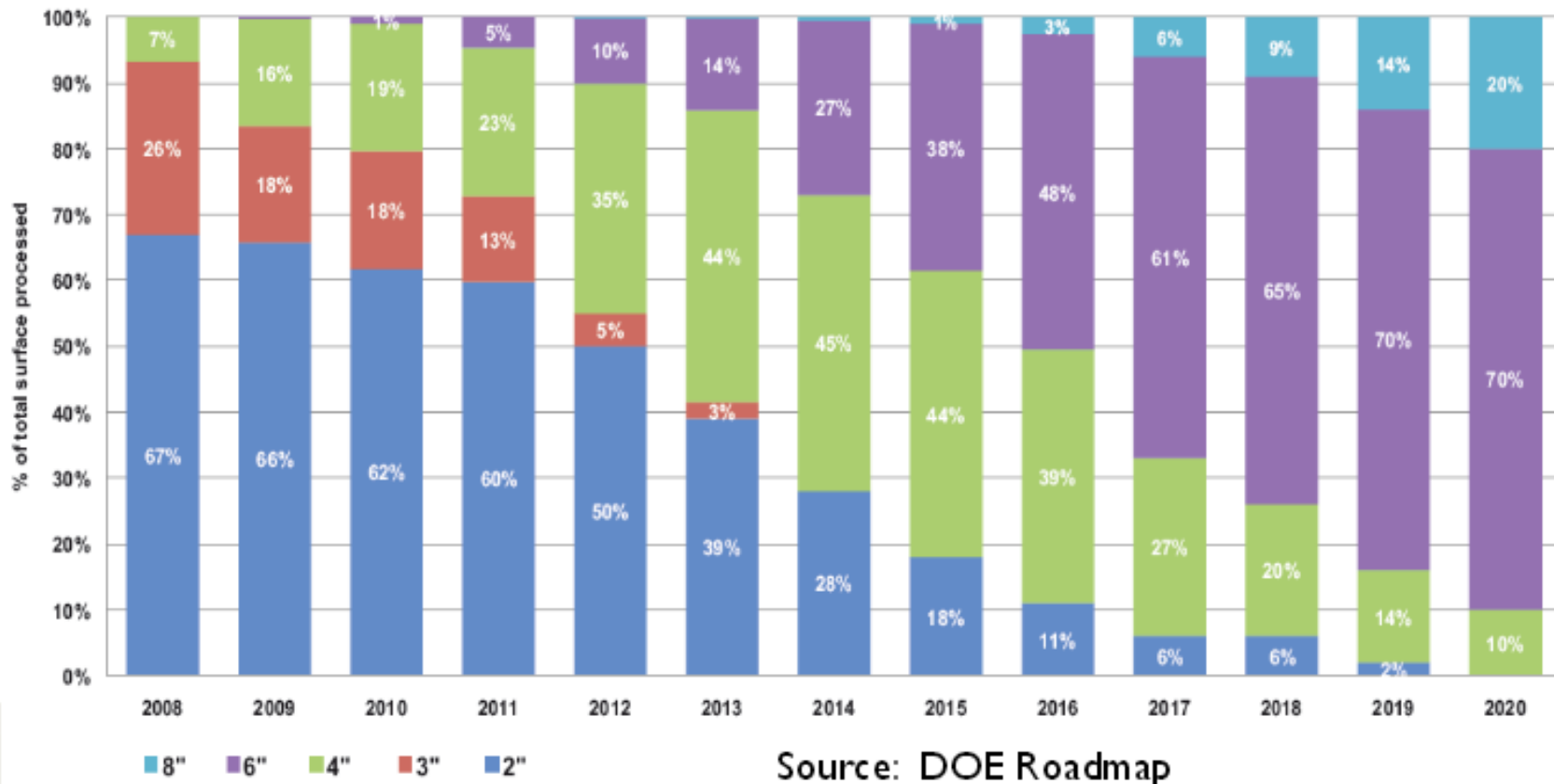


LED production



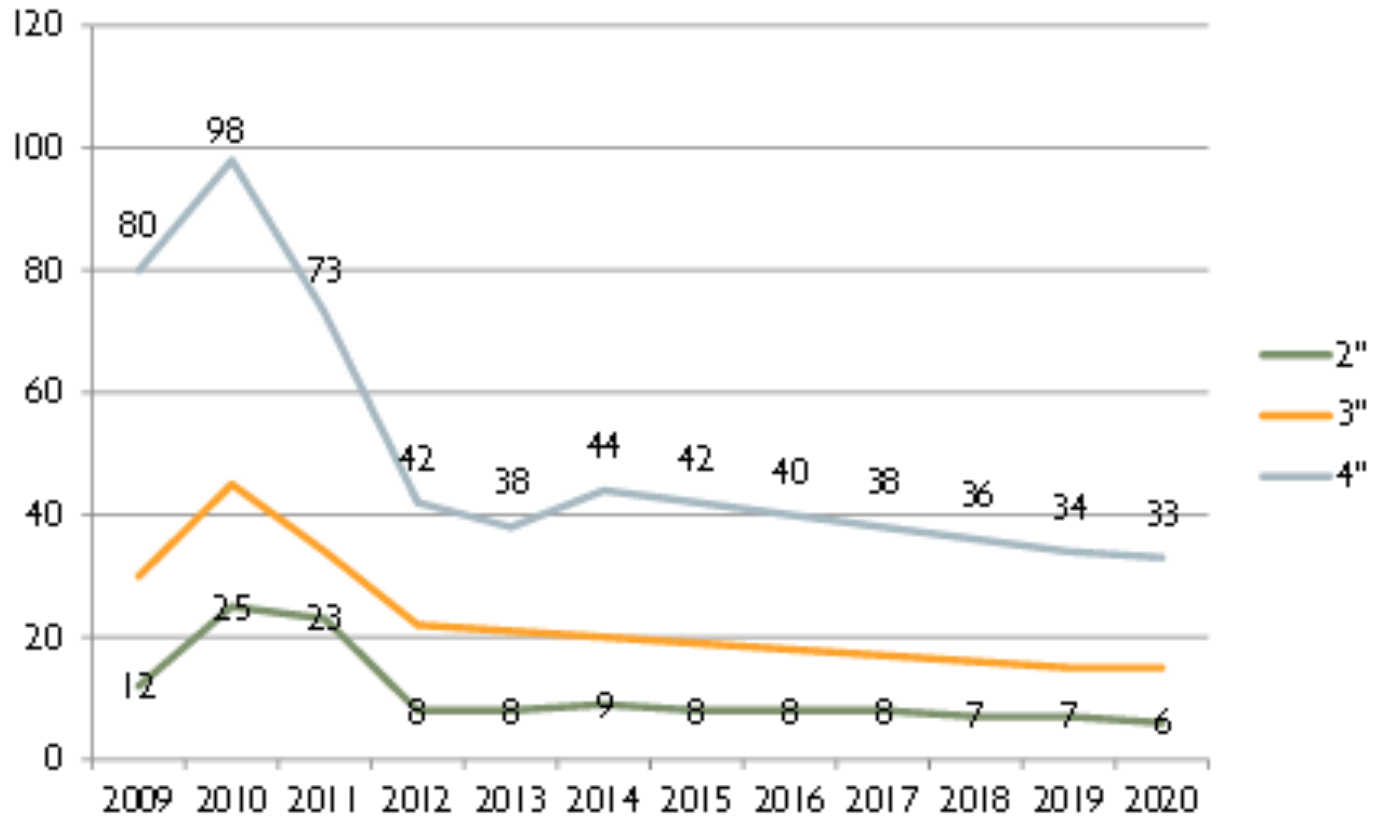
- 40 Bmm² = 8 soccer fields / year
- 5 Million substrates (4 inch)
- Installed capacity is large enough

Sapphire Substrates for LEDs: Diameter trends to 2020



Wafer size increases

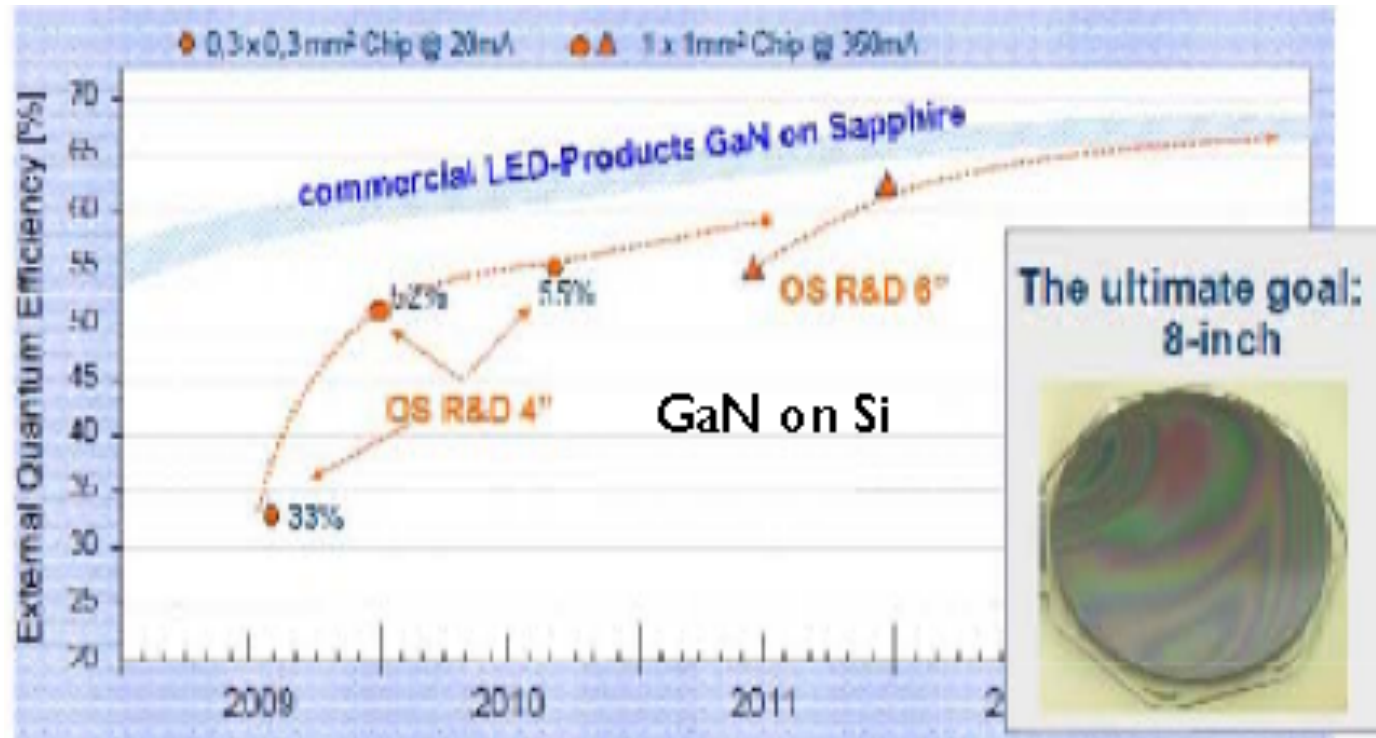
Sapphire wafer price forecast (\$)



Substrates for LEDs

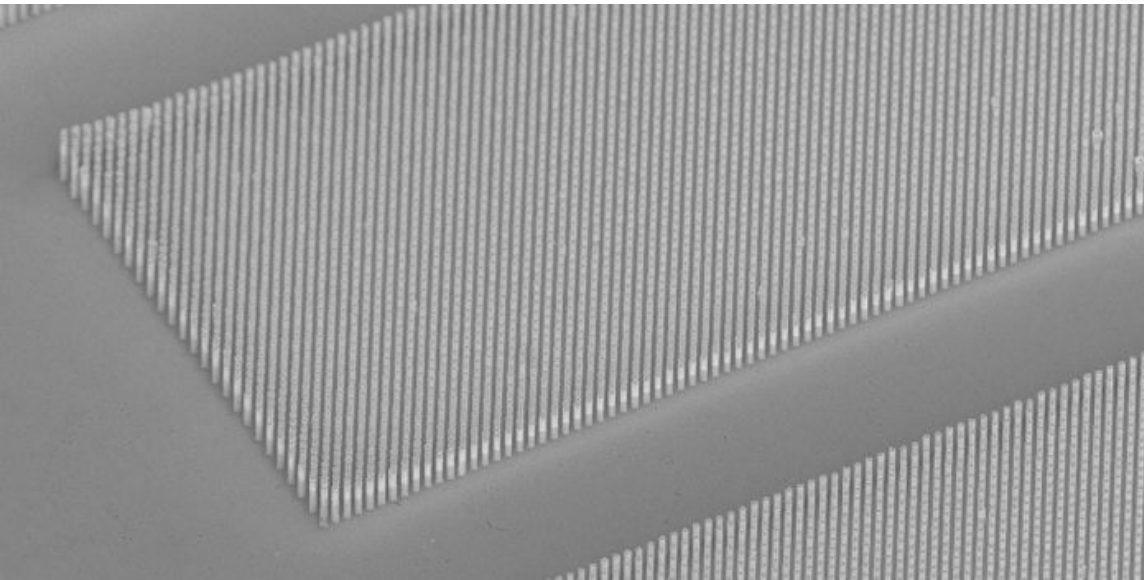
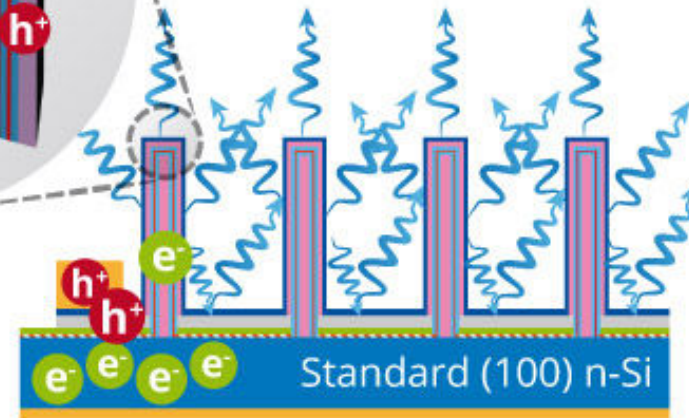
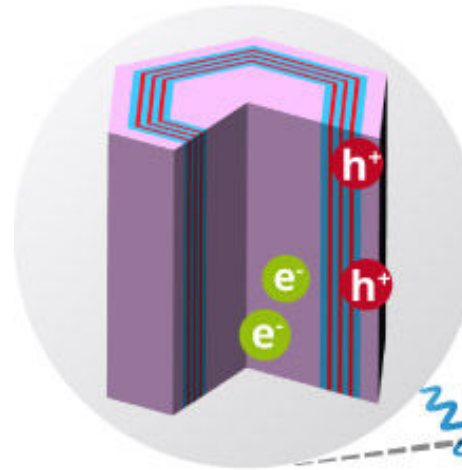
Some players on Si (111): Plessey (UK), Toshiba (JP), Lattice power (Ch), Samsung (Kr), OSRAM (Ge), LG (Kr), Epistar (Kr), Novagan (Sw)

- Large area (lower epitaxy and processing costs)
- Easy back process : Si is removed
- Epitaxy is more tricky but almost similar performance can be reached



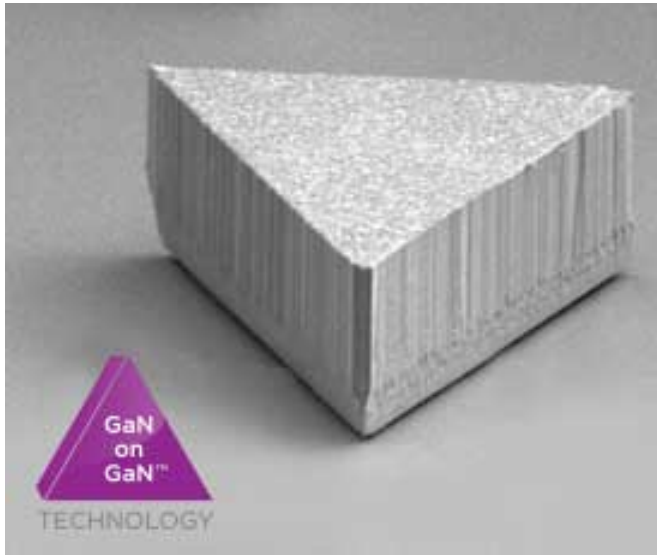
Substrates for LEDs

Si (100): : epitaxy difficult for 2D layers as the square surface symmetry induces two domains of wurzite material twisted by 90° . OK for nanowires \Rightarrow ALEDIA (Grenoble): Si (100) 8 inch



Substrates for LEDs

GaN substrate (Sora): better crystalline quality, higher efficiency, light extraction by simple process (triangular shape)



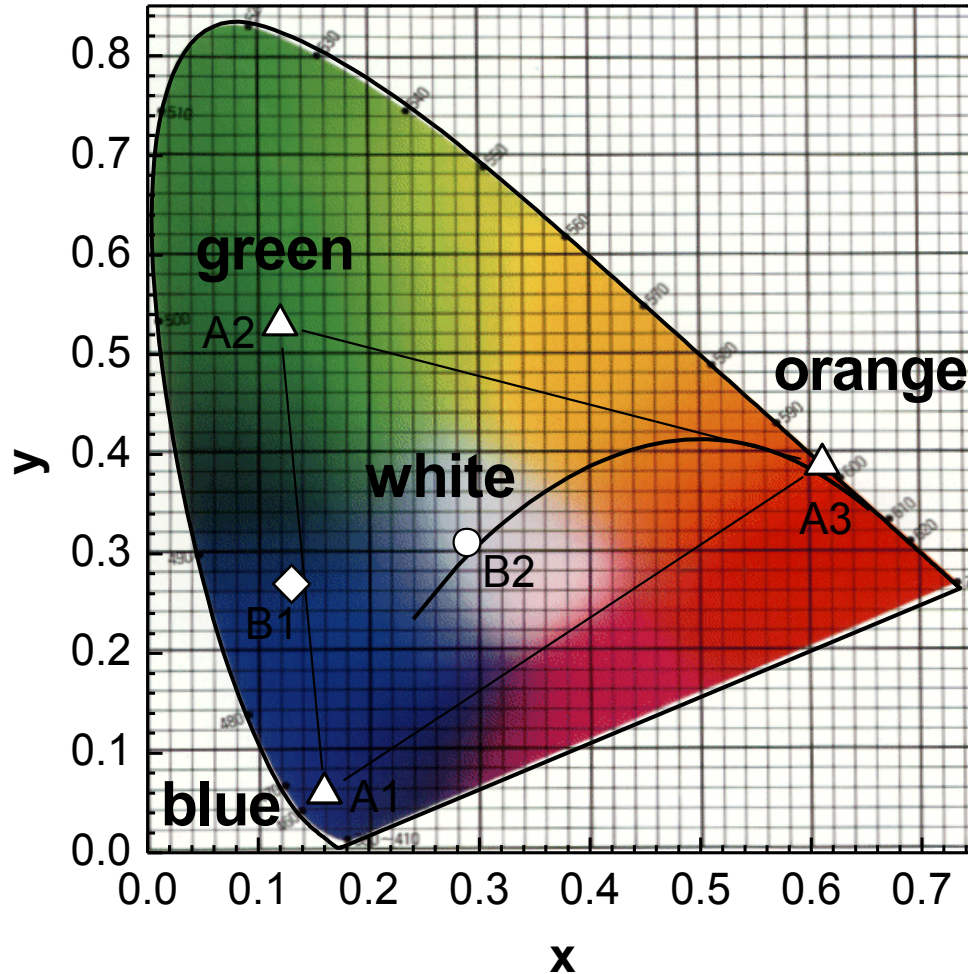
WPE=84% @ 1 A/cm²

⇒ All individual η close to unity !

Growth technique

	MBE	MOVPE
Point defects		Higher T_g
Dislocations		Lateral growth
N doping	OK	OK
P doping	Less H problem Lower T_g : less compensation, better for QW grown below	
InGaN		More localisation ? Less point defects ?
InN	Low T_g (P-MBE)	
Throughput		Developed large systems

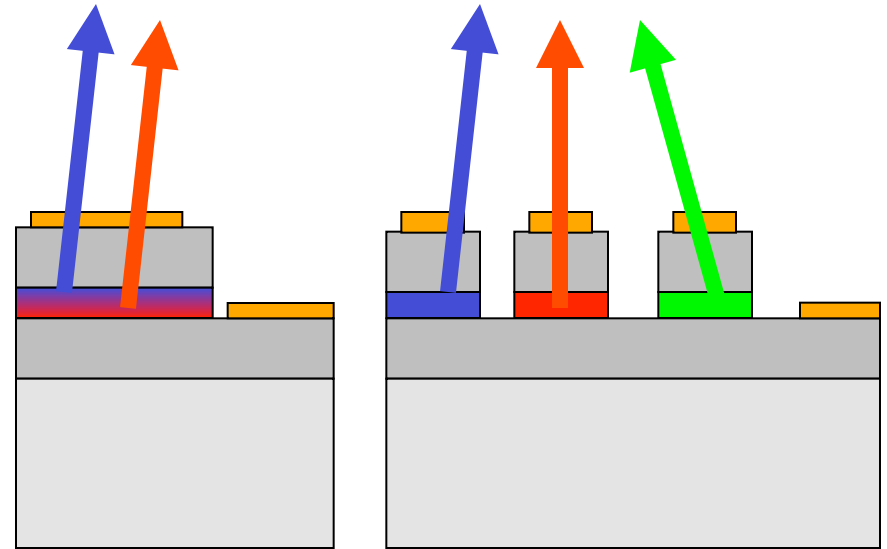
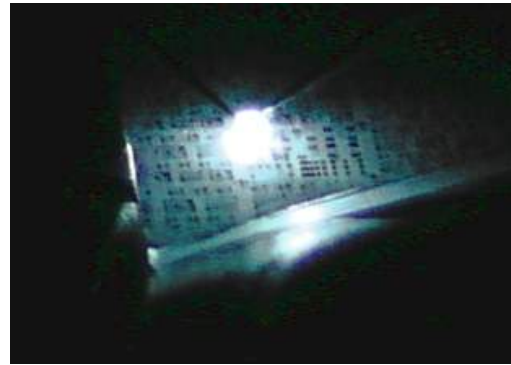
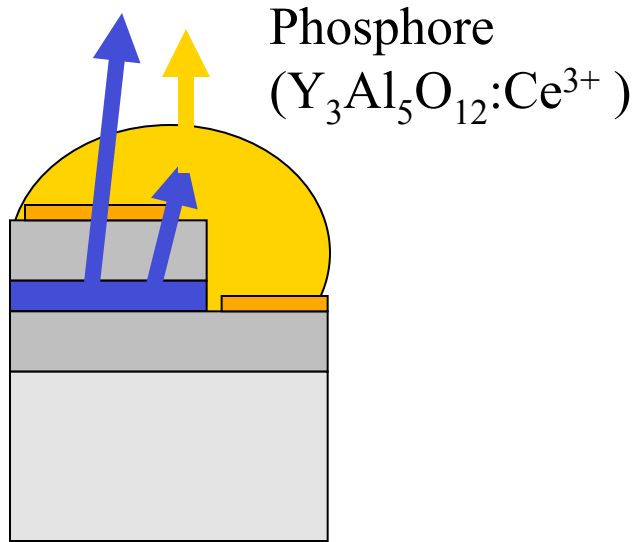
White from color mixing



Black body equivalent temperature : warm white (red) = lower T. Cold white (blue) = higher temperature

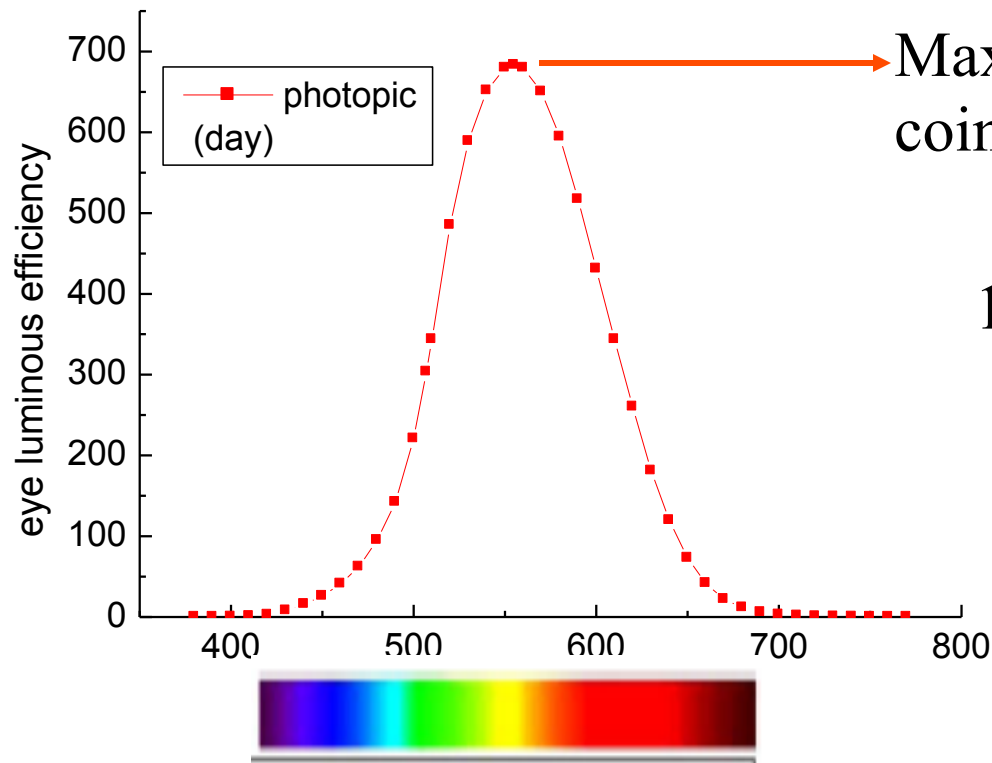
Phospors versus RGB

Usual approach: Blue/
yellow conversion



Integrated approach (epitaxy):
ideal solution but still less
efficient and more complicated

Eye perception of light and lumen



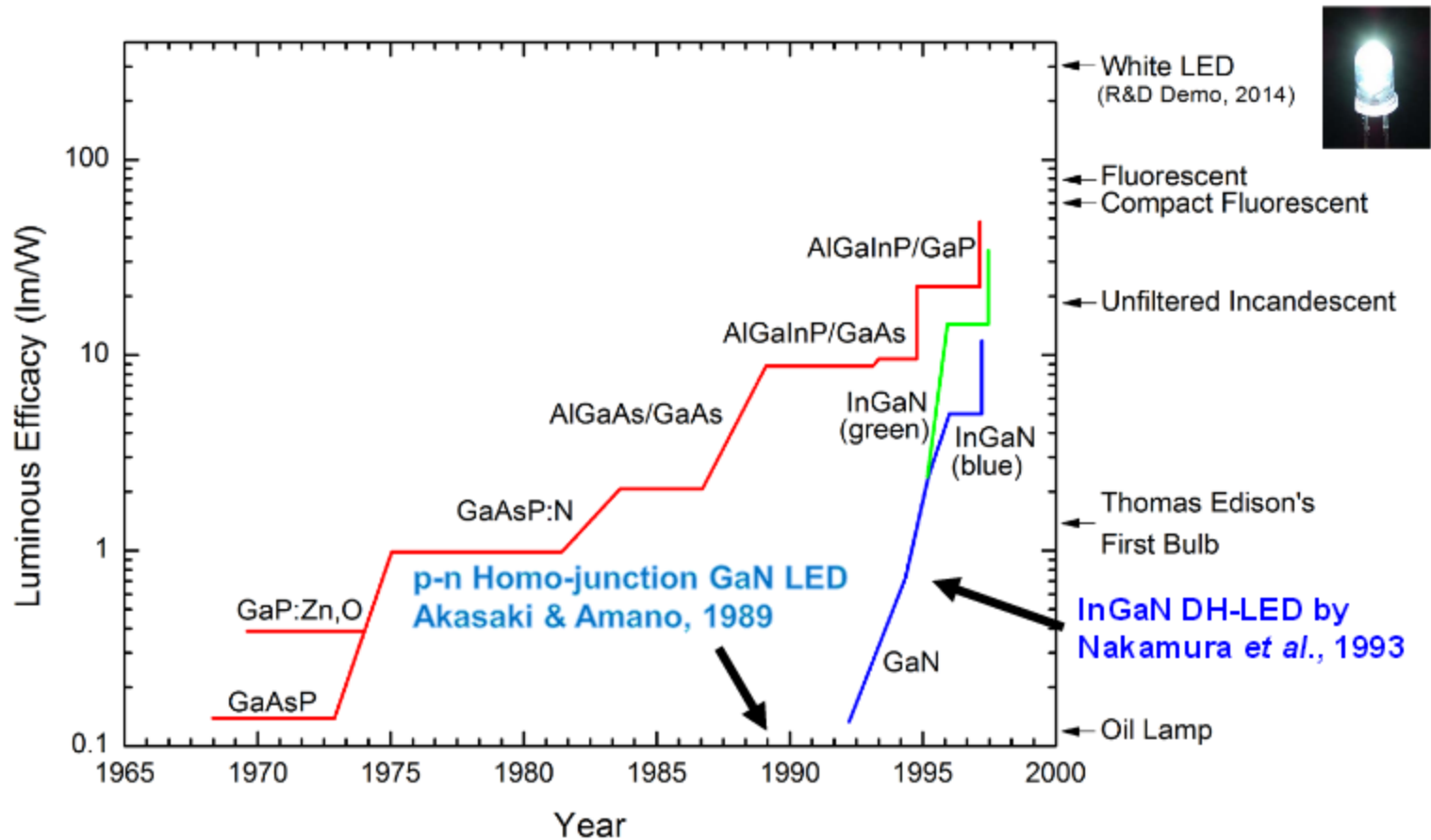
Maximum at 555nm (not a coincidence !!)

1 lumen is the luminous flux of a monochromatic source at 555 nm with a power = $1/683$ W

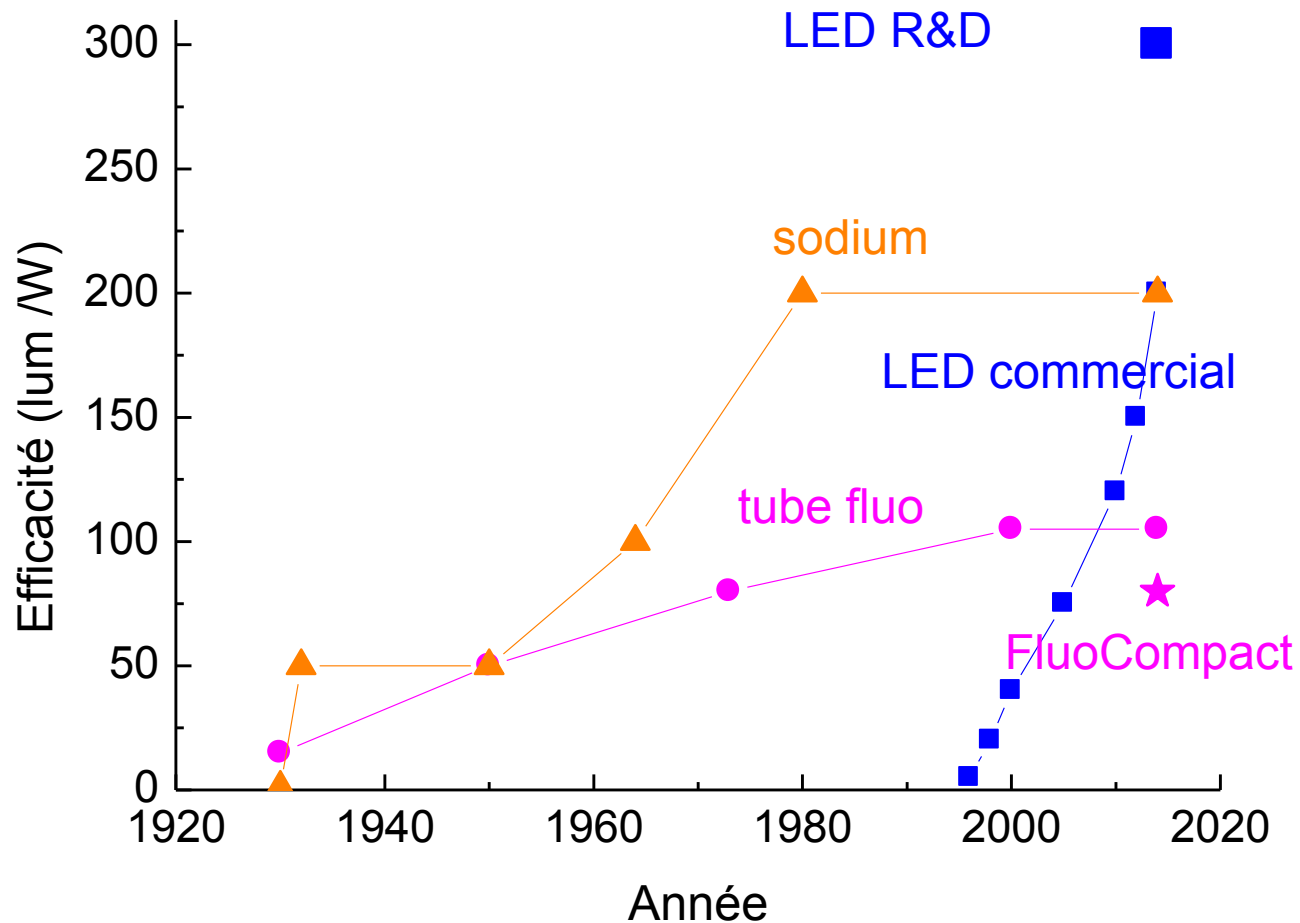
Average value from 430 to 630 nm : 350 lum / W

~ Ideal lighting source for humans

Historical perspective on LED efficacy



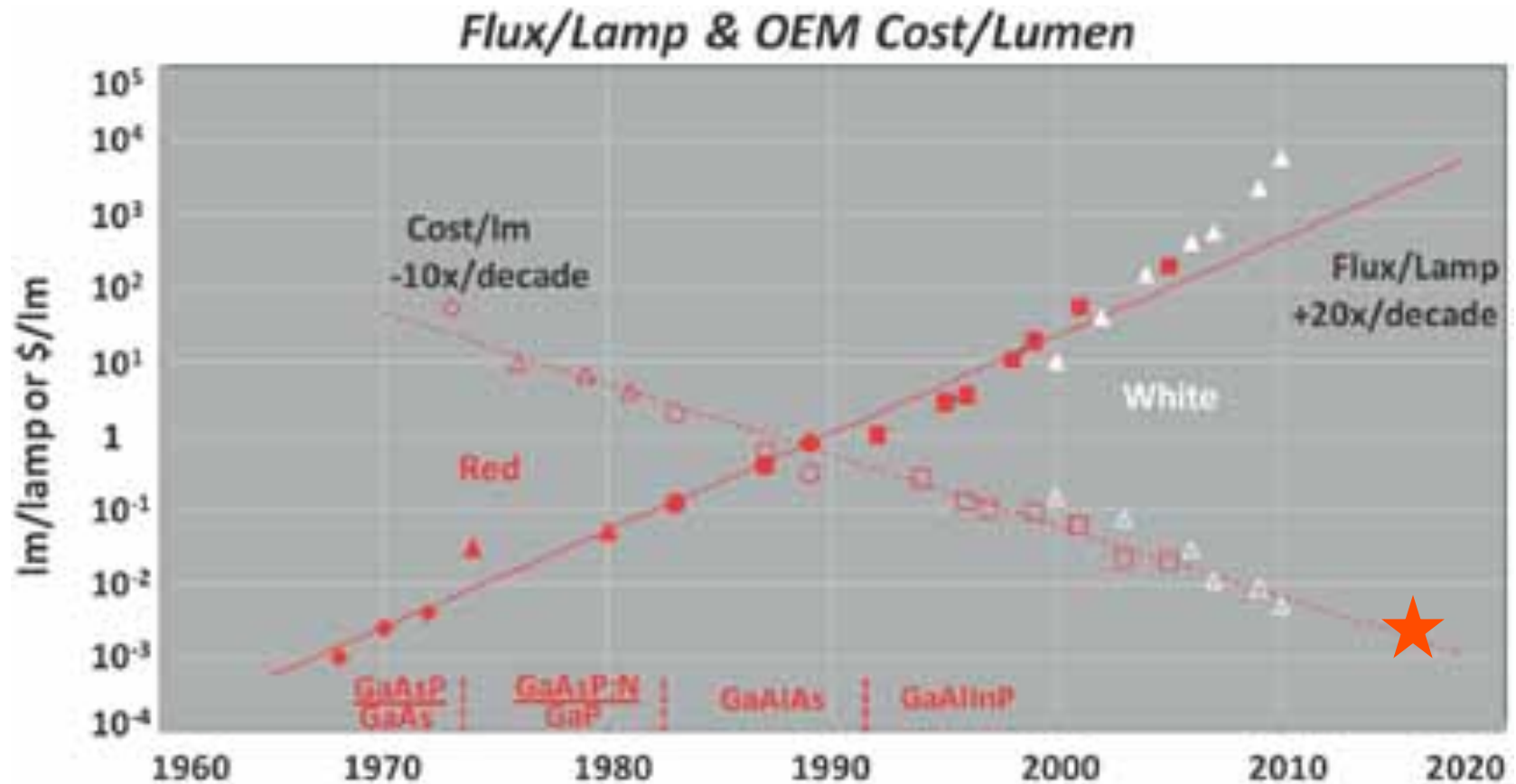
Historical perspective on efficacy for lighting



Revolution rather than evolution !

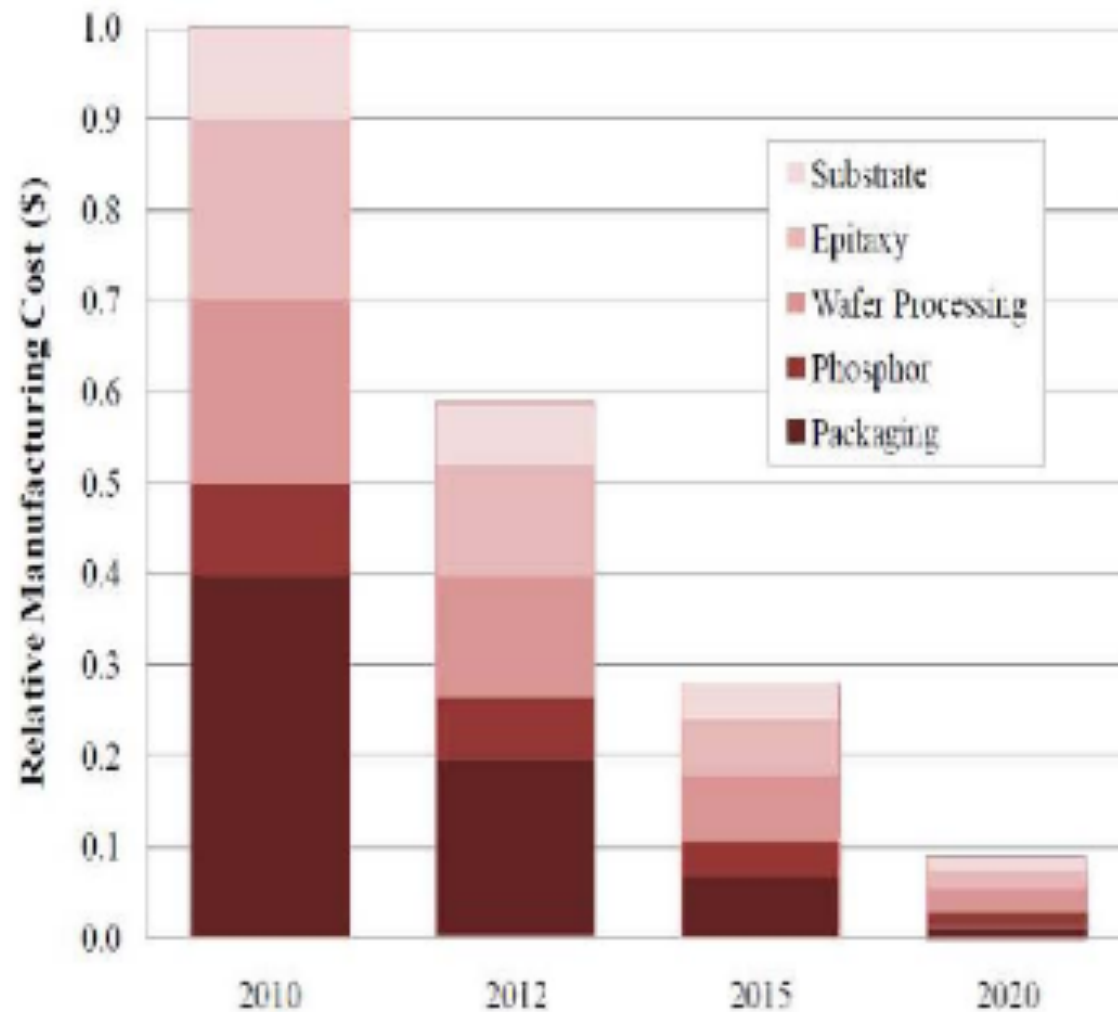
Best LEDs close to the limit !

Haitz' Law: Cost \downarrow 10x & Performance \uparrow 20x per decade.



About \$2/klm in 2015 (1 klm is the output of former 60W incandescent bulbs)

Epitaxy is the enabling technology but is only part of the cost



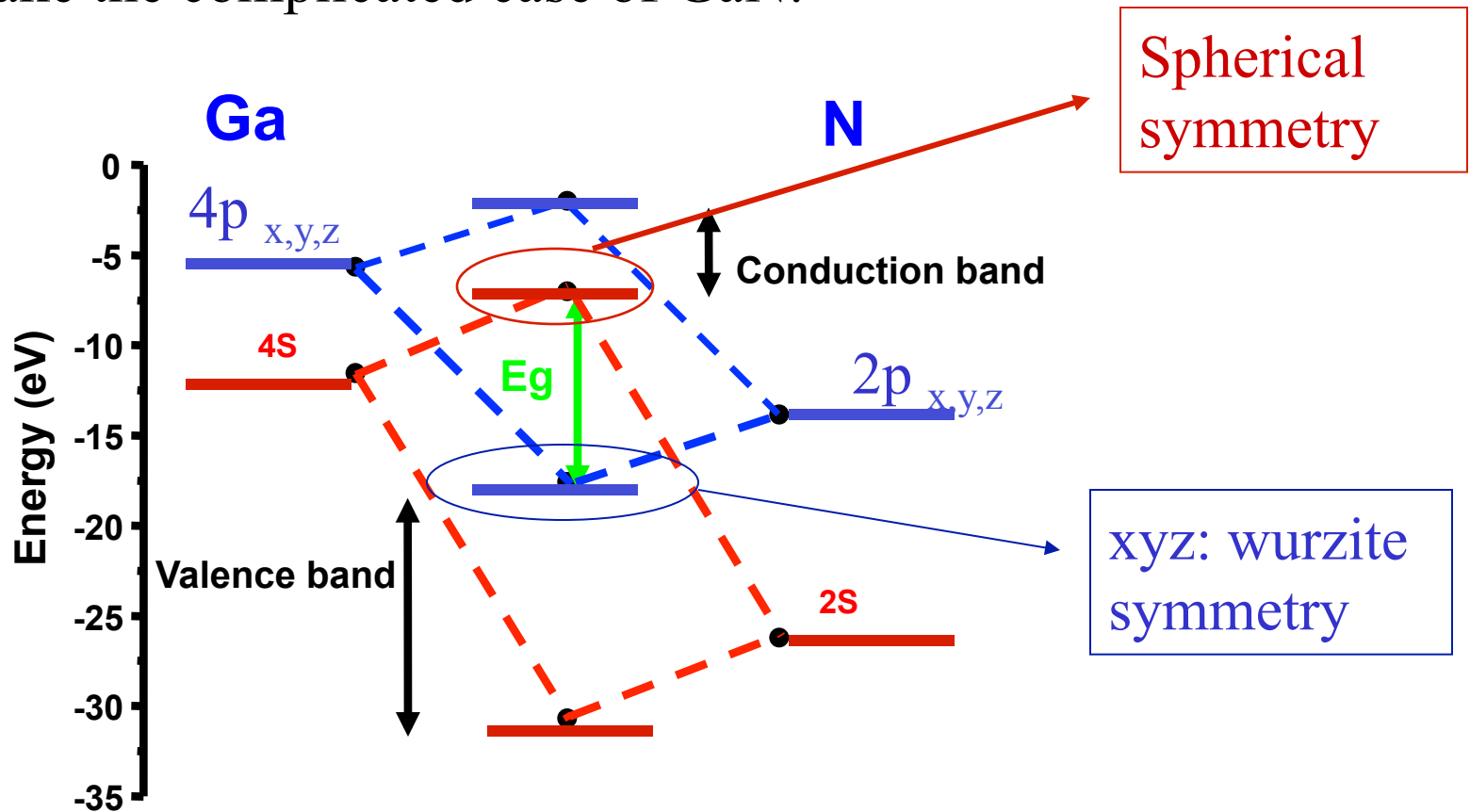
CONCLUSION

- Tremendous efforts in academic and industrial R&D have been dedicated to epitaxy for LEDs
- But epitaxy is only part of the game: design, process, packaging...and economic issues

$$\left| \vec{E} \cdot \vec{r}_{vc} \right|^2$$

Dipolar matrix element r_{vc} : Intrinsic parameter which depends on the band structure of the QW material

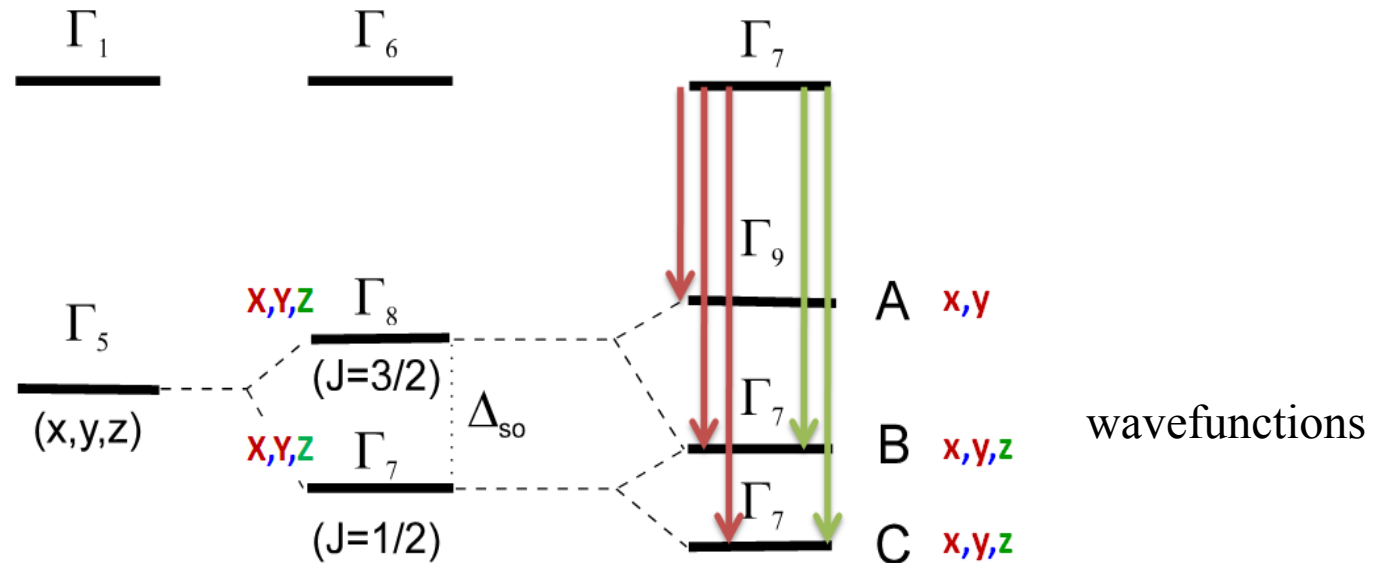
Let us take the complicated case of GaN:



Valence band structure of GaN:

- x,y and z not equivalent in wurtzite (crystal field)
- spin orbit coupling small (light atoms)

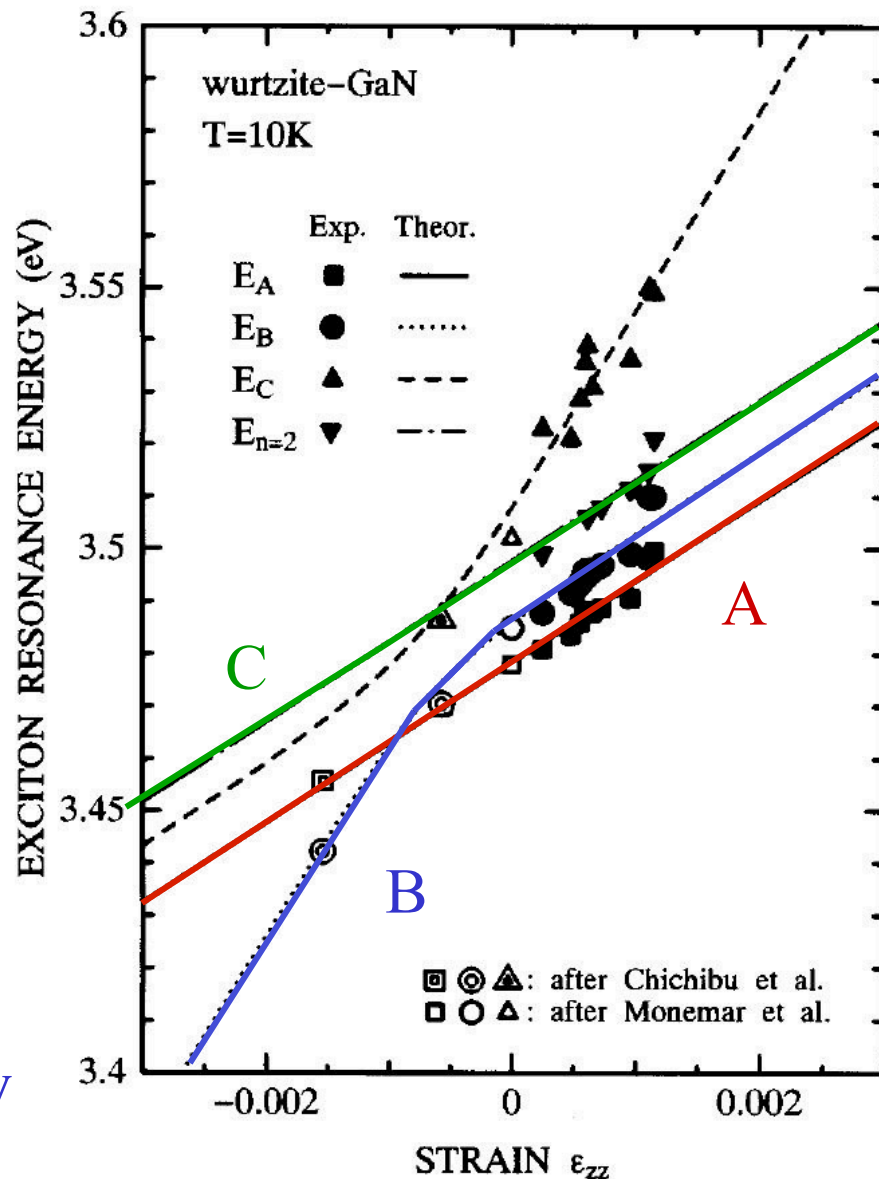
Similar value



Transition polarisation:

- A (x,y) \Rightarrow \mathbf{E} in x,y plane, $\perp c$
- B,C (xyz) \Rightarrow any \mathbf{E} , amplitude depends on z/x,y ratio

Strain modifies the crystal field and the valence band structure: energy and change



Wavefunctions:

$C \Rightarrow xy$

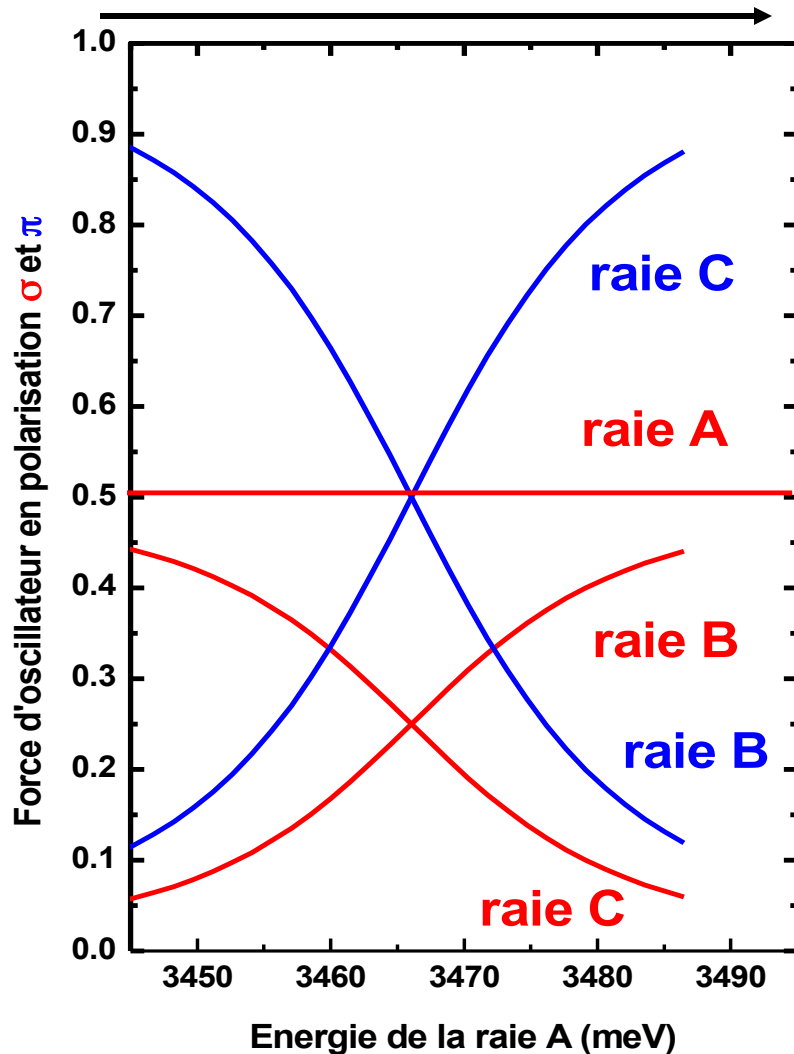
$B \Rightarrow z$

$C \Rightarrow xy$

Wavefunctions:

$B \Rightarrow xy$

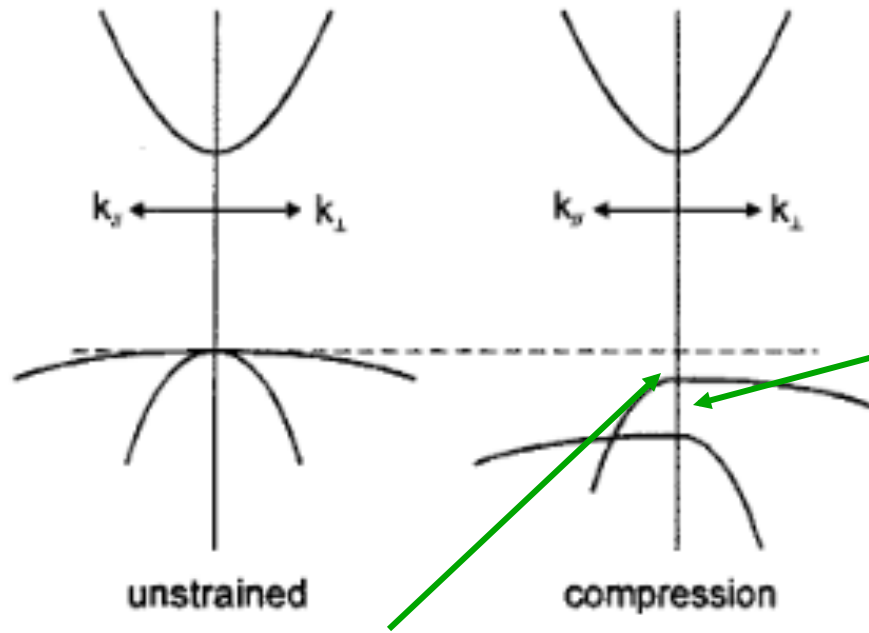
extension strain compression



There is some choice (substrate, buffer layer, growth conditions...) on the strain state during the epitaxy to favor one transition or another.

Not so important for GaN, but more important for AlGaN where the top valence band become A (emitting along z) + B (emitting in the xy plane)

Another famous example: strained InGaAs laser



InGaAs the VB degeneracy is lifted.

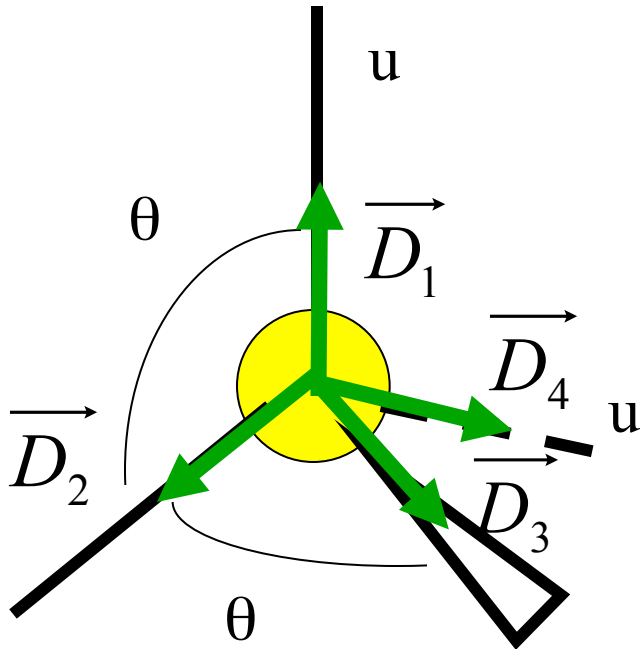
The in plane effective mass becomes smaller

⇒ the effective density of states decreases

⇒ the threshold decreases

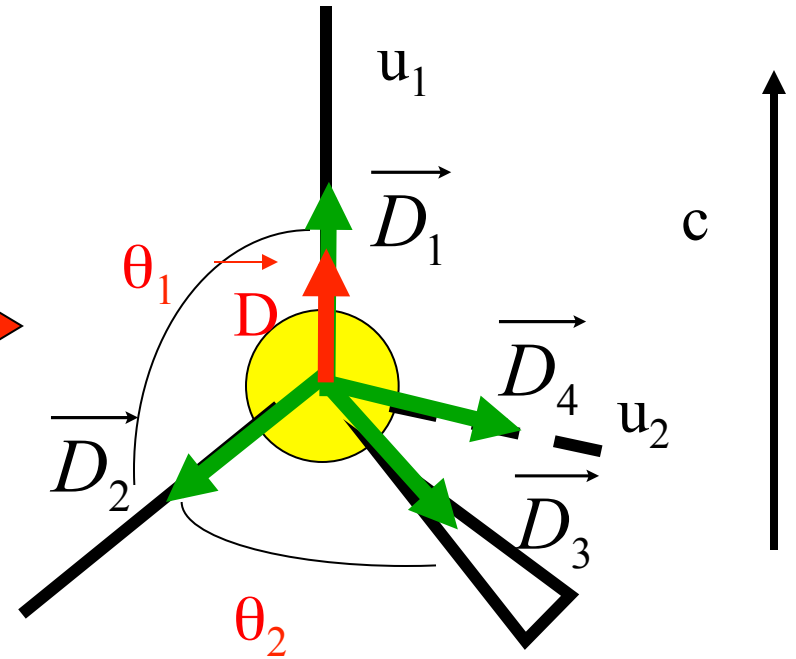
Polarization on the atomic level

Ideal tetrahedron



$$\vec{D}_1 + \vec{D}_2 + \vec{D}_3 + \vec{D}_4 = \vec{0}$$

Real distorted tetrahedron*

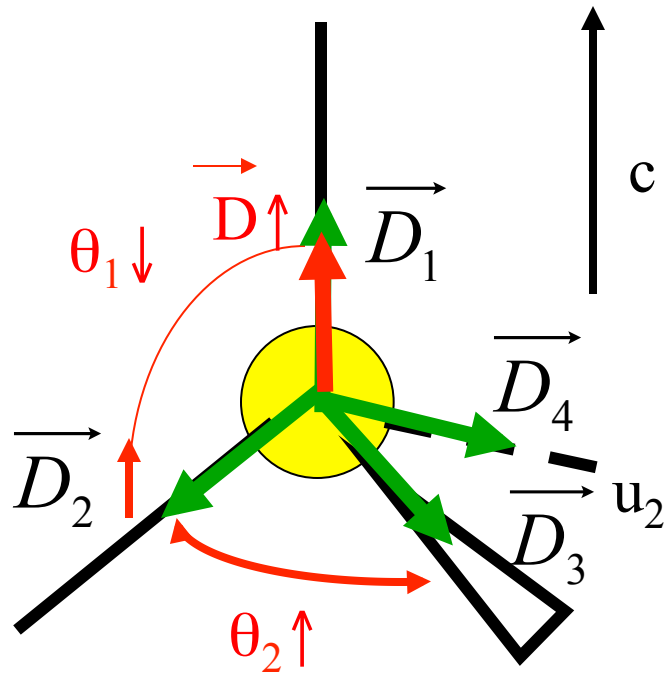


$$\vec{D}_1 + \vec{D}_2 + \vec{D}_3 + \vec{D}_4 = \vec{D}$$

and $\vec{D} // c$

Wurzite nitrides

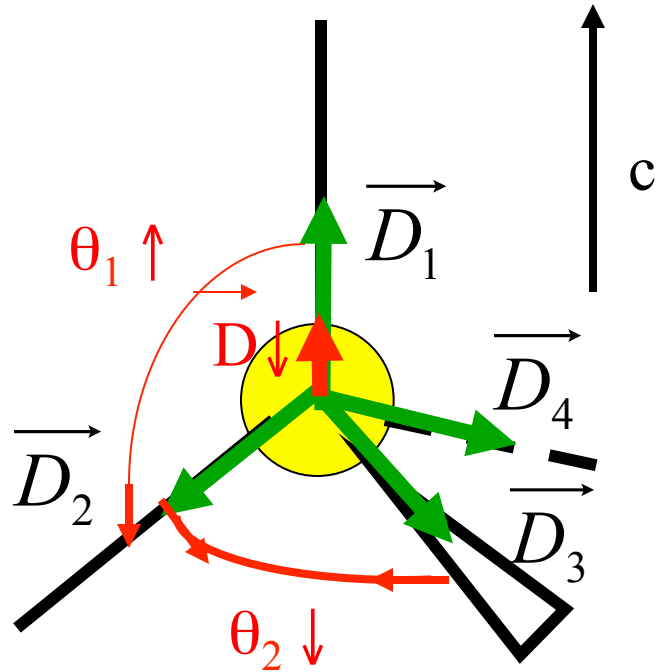
Spontaneous polarization: distortion of the cell / ideal structure (c shorter, $c/a < 1.633$)



Growth on a substrate with a larger a

\Rightarrow tensile stress, deformation of the cell, increase of a and decrease of c

\Rightarrow piezoelectric polarization added to the spontaneous polarization



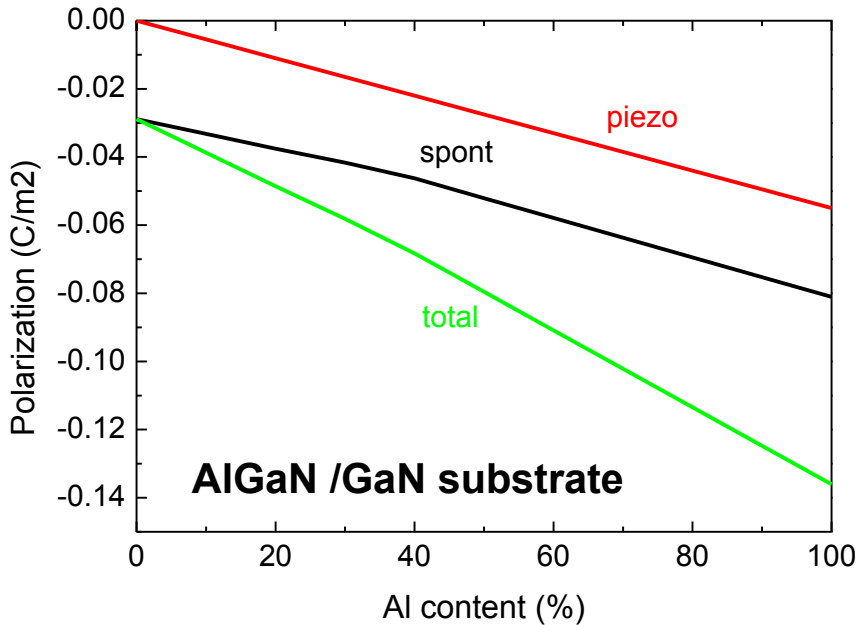
Growth on a substrate with a smaller a

\Rightarrow Compressive stress, deformation of the cell, decrease of a and increase of c

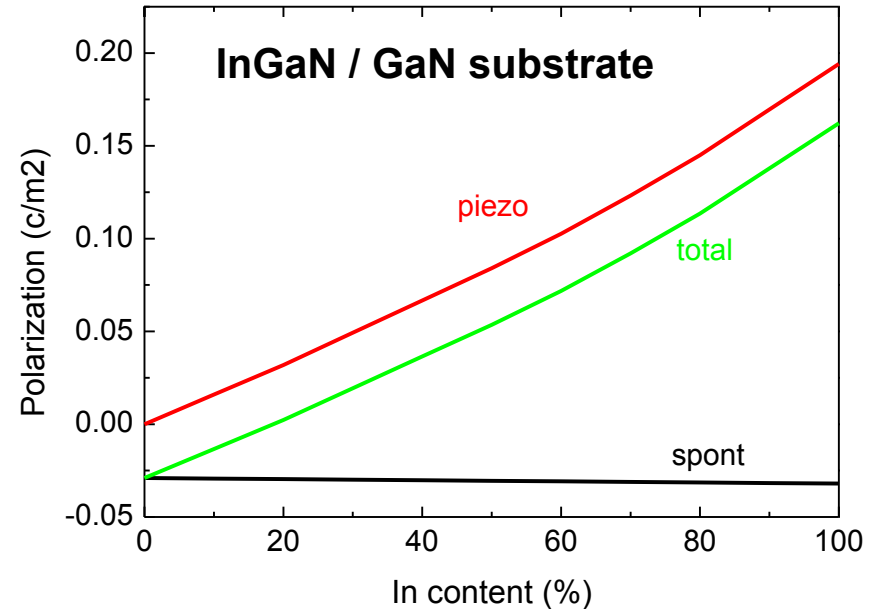
\Rightarrow piezoelectric polarization opposite to the spontaneous polarization

Polarization in wurzite nitrides

Polarization in AlGaN



Polarization in InGaN



For strained heterostructures :

$$P_{\text{AlGaN}} < P_{\text{GaN}} < P_{\text{InGaN}}$$

Defeating Compensation in Wide Gap Semiconductors by Growing in H that is Removed by Low Temperature De-Ionizing Radiation

James A. Van VECHTEN*, J. David ZOOK¹, Robert D. HORNING¹ and Barbara GOLDENBERG¹

Center for Advanced Materials Research, Oregon State University, Corvallis, Oregon 97331-3211, USA

¹*Sensor and System Development Center, Honeywell Inc., Bloomington, Minnesota 55420, USA*

(Received April 27, 1992; accepted for publication July 18, 1992)

We propose a general method to obtain high conductivity of either type in wide gap semiconductors where compensation normally limits conductivity of one or both types. We suggest that the successes of Amano *et al.* and of Nakamura *et al.* in obtaining more than 10^{18} cm^{-3} holes in GaN are particular examples of the general process that we propose.

KEYWORDS: hydrogen, compensation, GaN, conductivity, wide gap semiconductors

Lattice location of hydrogen in Mg doped GaN

Wampler et al, JAP 90, 108 (2001)

Measurements by ion channeling to examine the lattice configuration of hydrogen in Mg doped GaN

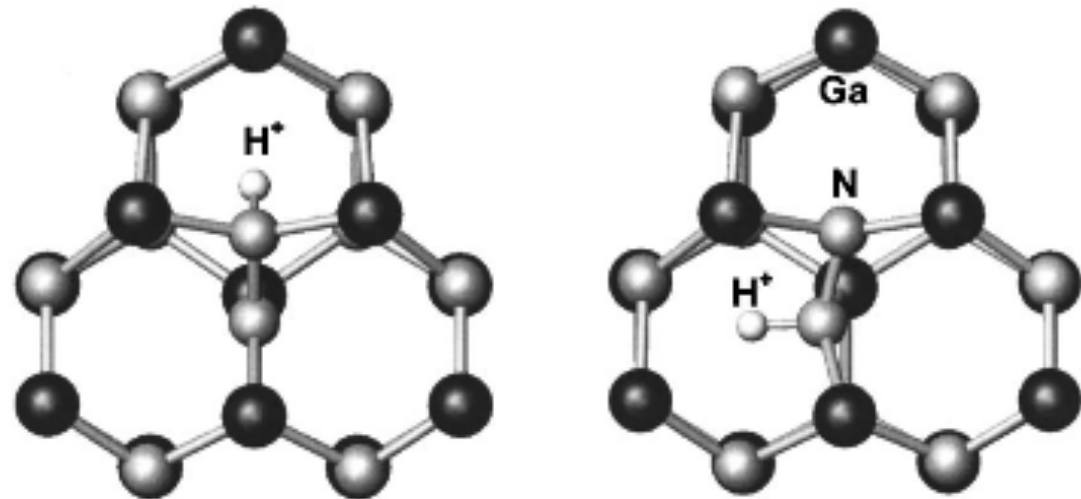


FIG. 1. Configurations for H bound to nitrogen split interstitial (viewed along the c axis) calculated by the density functional theory. The H is near the center of the trigonal channel in both cases.